

OEM Microscope Components for Integration



















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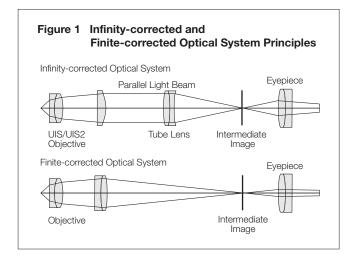
Welcome to UIS2 Optics

UIS2:

The System That Maximizes the Advantage of Infinity-corrected Optics

What is Infinity-corrected Optics?

UIS2 optics is an infinity-corrected optical system — in other words, a system in which light passes from the specimen through the objectives without forming an image along the way. Instead, it travels in the form of infinity parallel rays to the tube lens. The tube lens is where the intermediate image is formed, whereas in finite-corrected optics, this is done by the objective.



Advantages of Infinity-corrected Optics

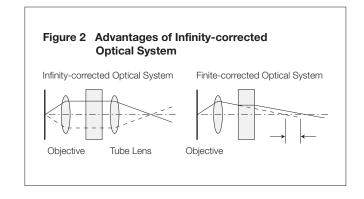
This system, known as "infinity-corrected optics", offers a number of advantages:

- There is no change in magnification even when the distance between the objective and tube lens is altered.
- With the total magnification remaining constant, there is no image aberration — even when prisms or sliders are interposed between the objectives and the tube lens.

As thousands of users have found by experience, these advantages are crucial to composing the ideal microscope optical system. What's more, it is even possible to freely insert or remove intermediate attachments in the parallel rays of light between the objectives and tube lens, allowing the creation of

user-specific or task-specific optical systems. To establish real flexibility with such a system, it is necessary to eliminate the occurrence of coma aberration.

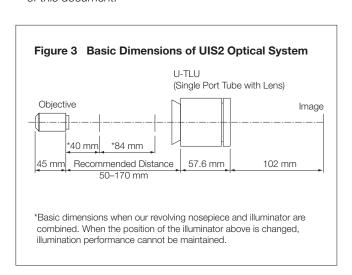
*In UIS2 Objectives, the parfocal distance is designed at 45 mm and the focal length of the tube lens is 180 mm.



Basic Dimensions of UIS2 Optical System

The UIS2 optical system optimally corrects aberration with a dedicated telan lens and an eyepiece so that the coma aberration and flatness are not degraded even when the telan lens exit pupil position is changed by changing the objective and telan distance. This makes it possible to use a distance of 50 mm to 170 mm from objective mounting position to the single port tube with lens.

*Coma aberration: refer to the optical terminology at the end of this document.



Features of UIS2 Objectives

UIS2 objective lenses provide compatibility (screw diameter, optical performance) with the UIS optical system and have the following features compared to conventional objectives.

1. Wavefront Aberration Control

The Olympus UIS2 objectives set a new standard, with wavefront aberration control in addition to common performance standards of NA and W.D. Olympus challenges farther advanced optics which has not been fulfilled by the conventional standards. We offer splendid performance objectives by minimizing the aberrations that lower resolution.

*Wave front aberration: refer to the optical terminology at the end of this document.

2. Objective Lenses with Splendid Image Parcentricity

High power SemiApochromatic UIS2 objectives make the centration tolerance between objectives on the microscope nosepiece keep the image within the enter of the field of view even with digital cameras. (50X or higher power in both MPLFLN and LMPLFLN series)

3. Improvement of Color Reproducibility

UIS2 objectives realize true color reproduction without any chromatic shifts using stringently selected high transmittance glass and advanced coating technology that provides high transmittance which is flat over an wide band wavelength. In addition, since the total optical system, including the tube lens is designed to reproduce a true color, clear images faithful to the specimen are obtained even with digital imaging.

4. Lightening

Weight has been reduced to approximately 2/3 that of conventional products by using an aluminum objectives barrel cover. This has the effect of lightening the load on the devices at objective up/down, suppressing vibrations by lowering the inertial force at objective switching, etc. (MPLFLN series, LMPLFLN series)

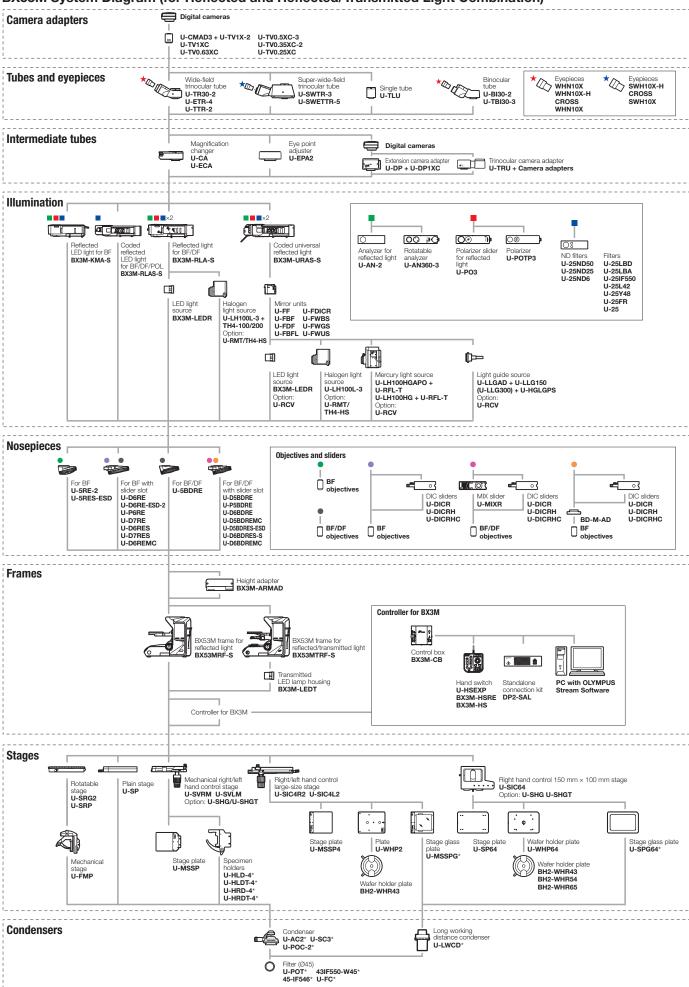
5. Adoption of Eco-lens

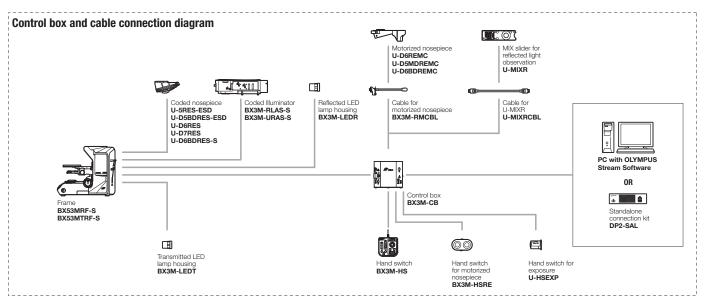
The glass materials of UIS2 objectives are all leadand cadmium-free eco-glass.

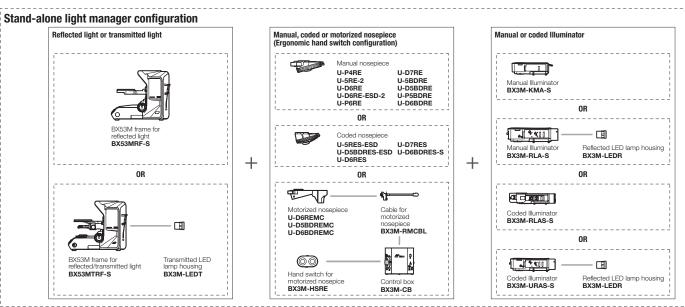
Based on our conviction that the UIS2 system maximizes the advantages of infinity-corrected optical systems, we confidently recommend the UIS2-featured Olympus microscope units for all your high-precision needs in research, inspection and production equipment.

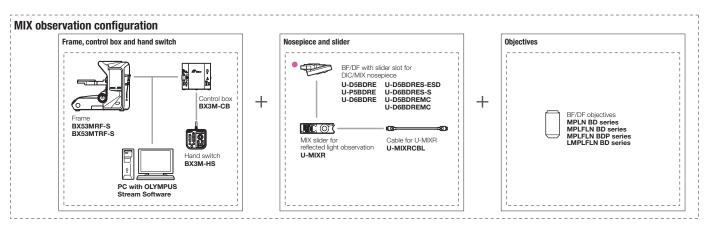
*Refer to the Olympus home page for detailed objective lenses specifications.

BX53M System Diagram (for Reflected and Reflected/Transmitted Light Combination)

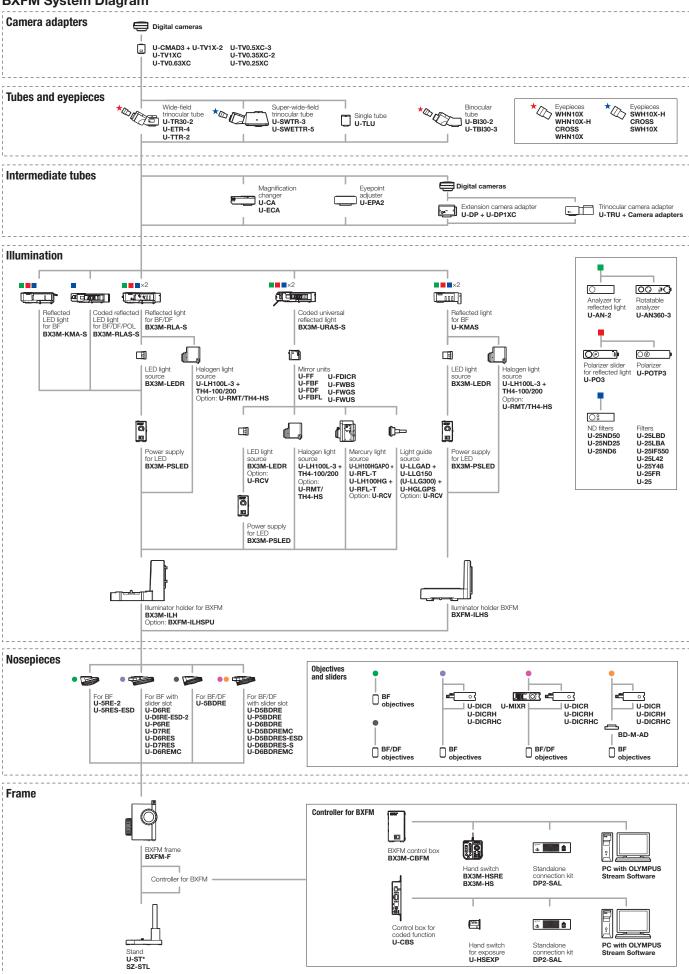


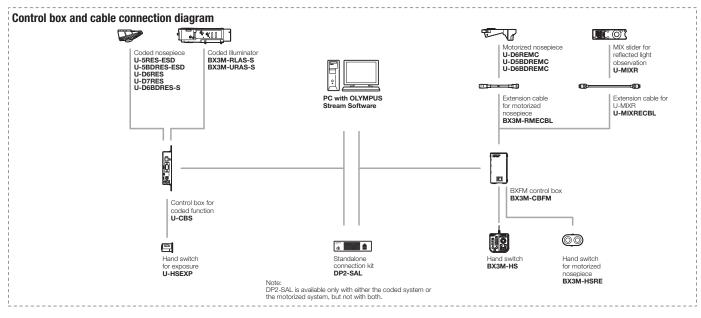


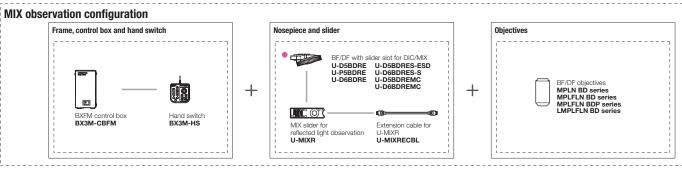


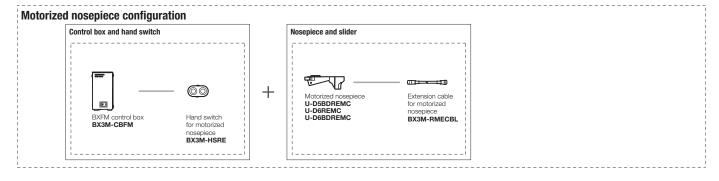


BXFM System Diagram

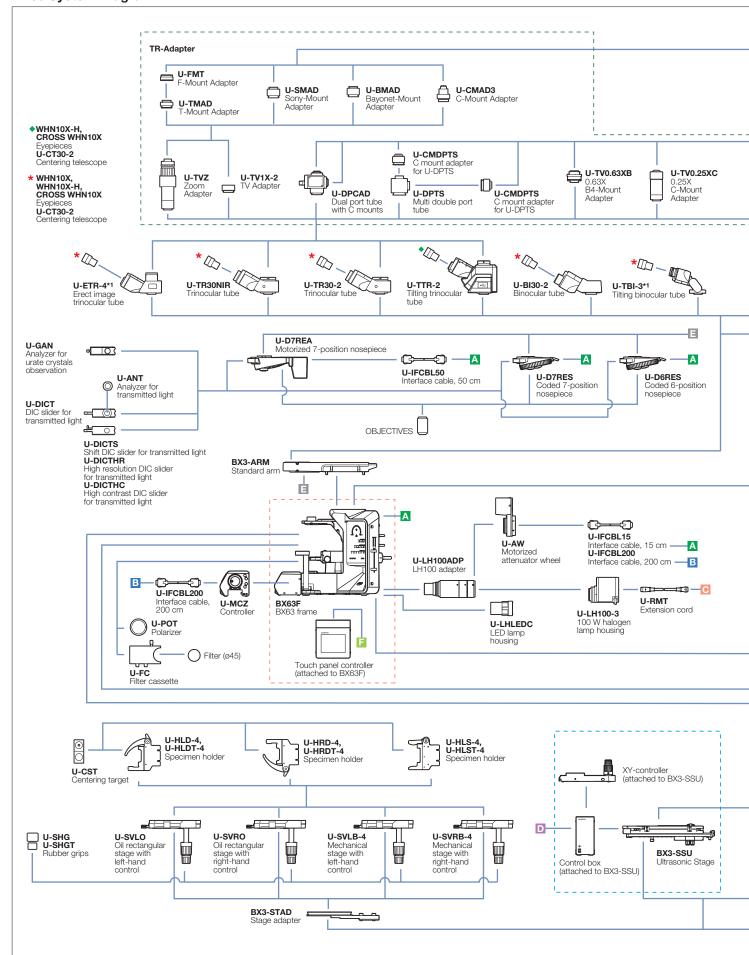






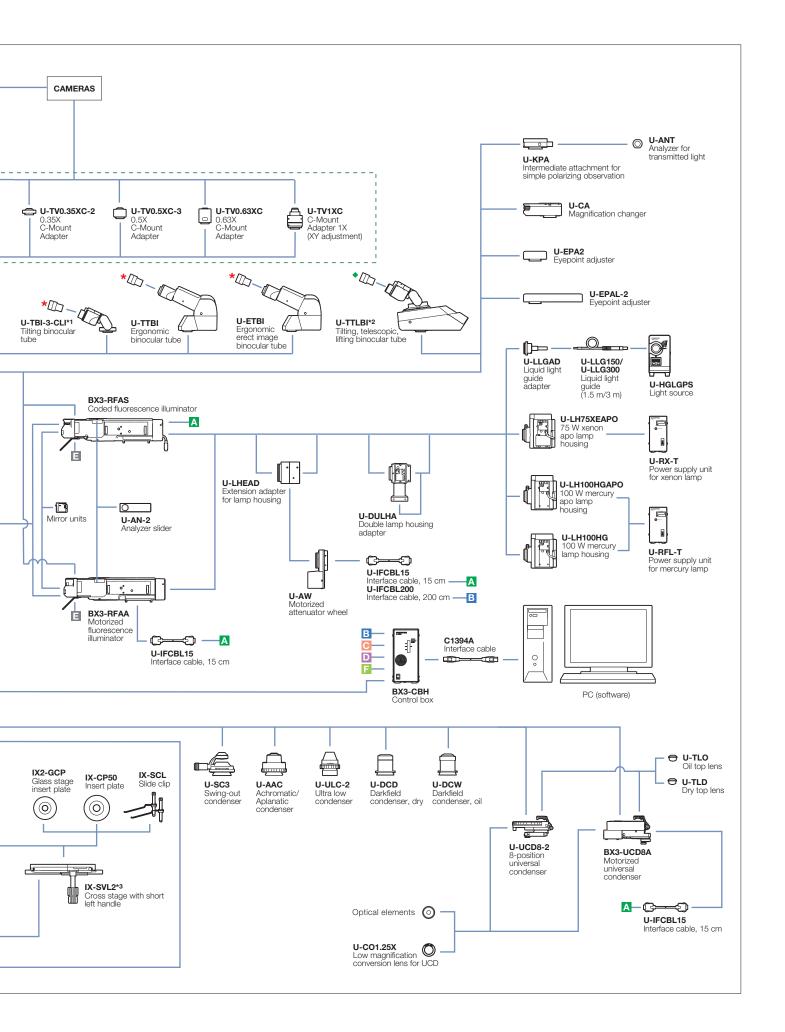


BX63 System Diagram

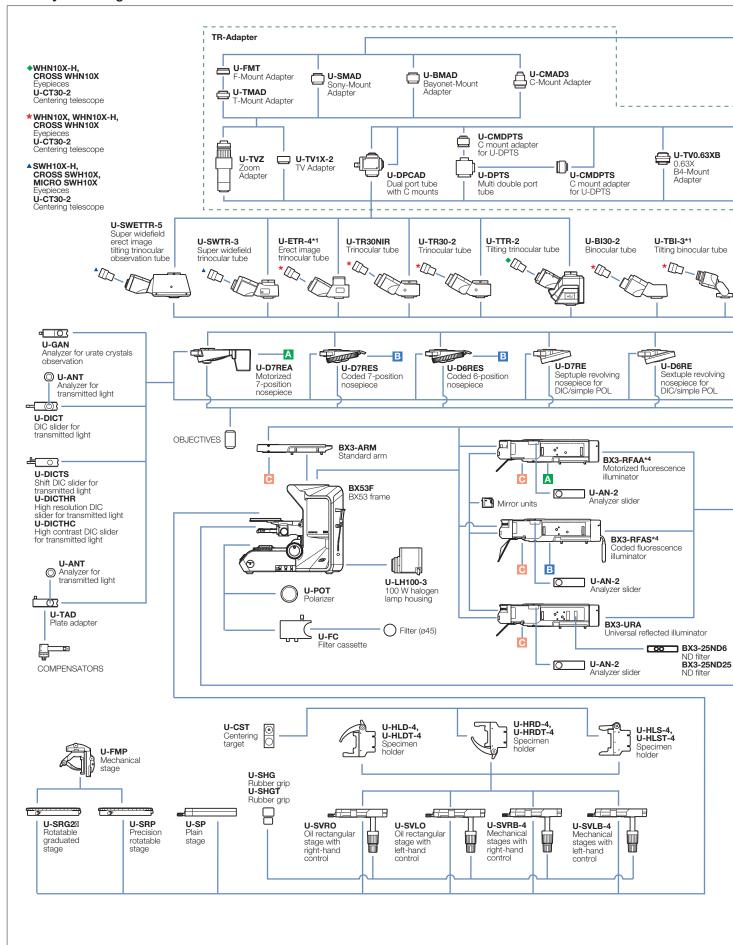


^{*1} Slight vignetting may occur in combination with an additional intermediate attachment or fluorescence illuminator. *2 Require an additional intermediate attachment or fluorescence illuminator.

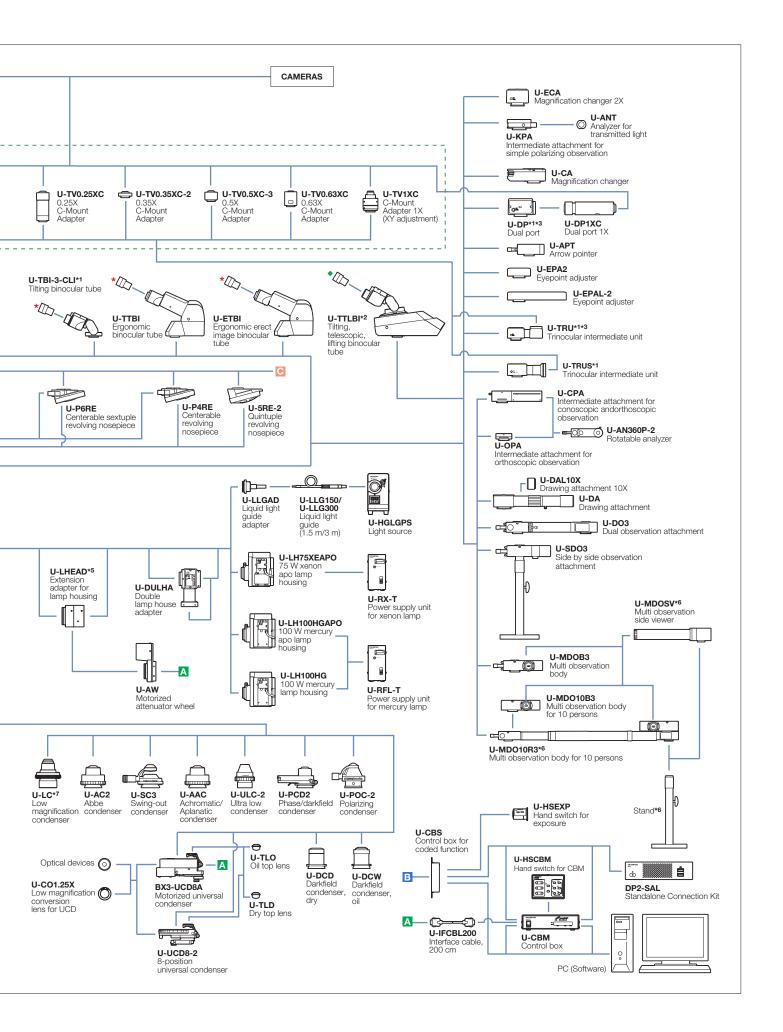
^{*3} Cannot be used with BX3-UCD8A and U-UCD8-2



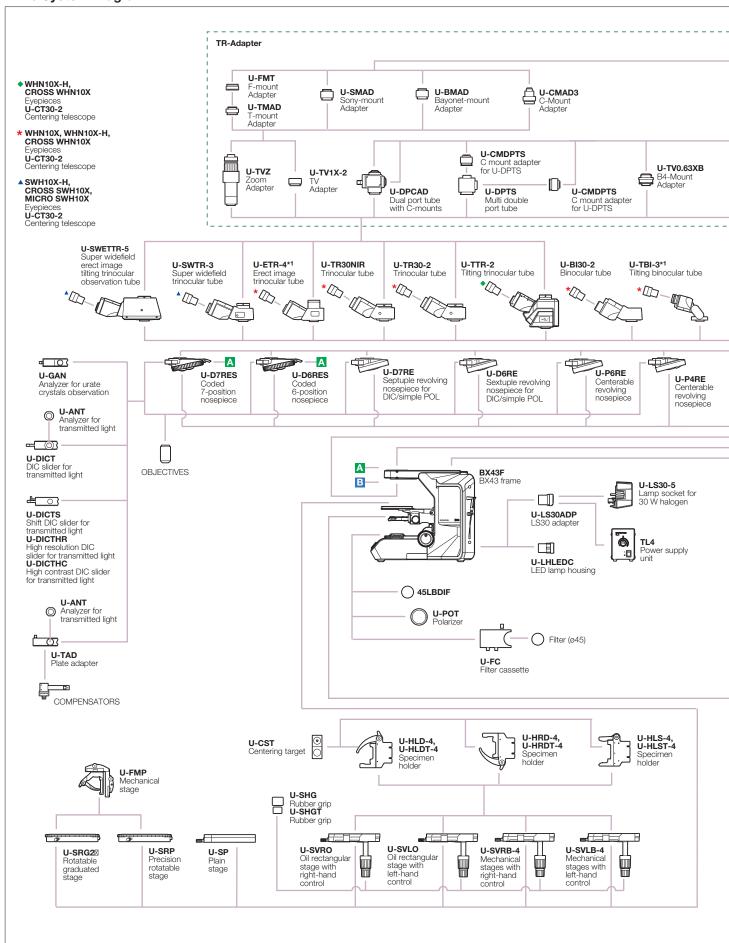
BX53 System Diagram



^{*1} Slight vignetting may occur in combination with an additional intermediate attachment or observation method. *2 Require an additional intermediate attachment or fluorescence illuminator. *3 Cannot be used with U-TTLBI. *4 Compatible with FN 22. *5 Cannot be used with BX3-URA. *6 Stand is a standard equipment of the U-MDOSV and U-MDO10R3. *7 An auxiliary lens is equipped.

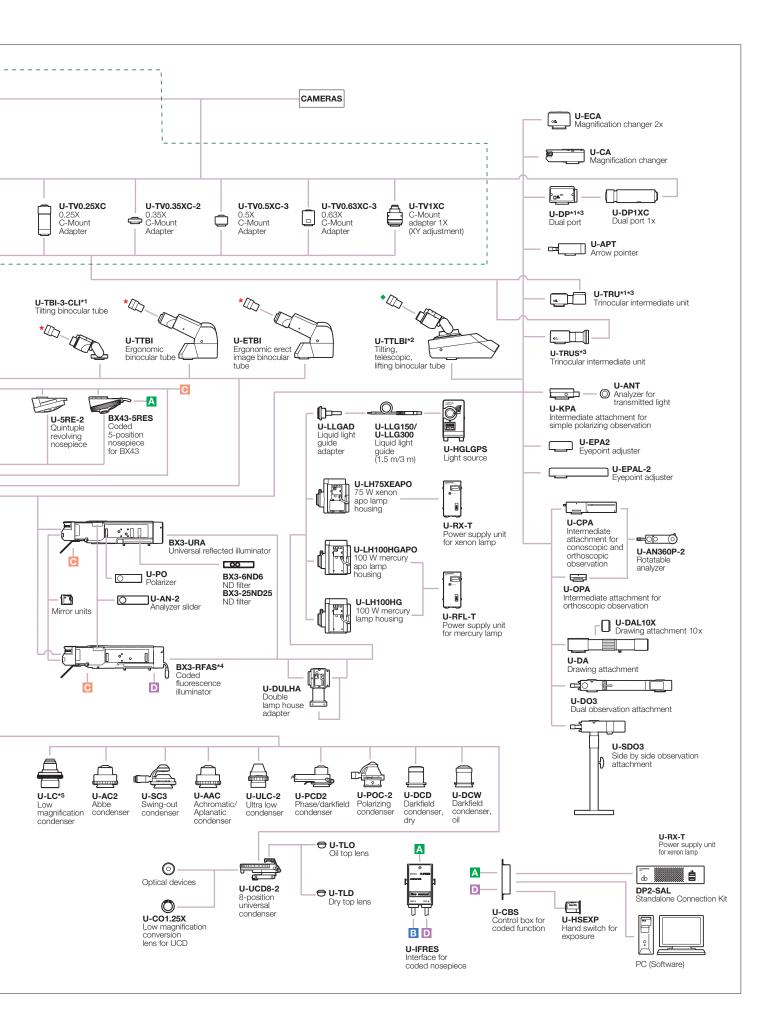


BX43 System Diagram

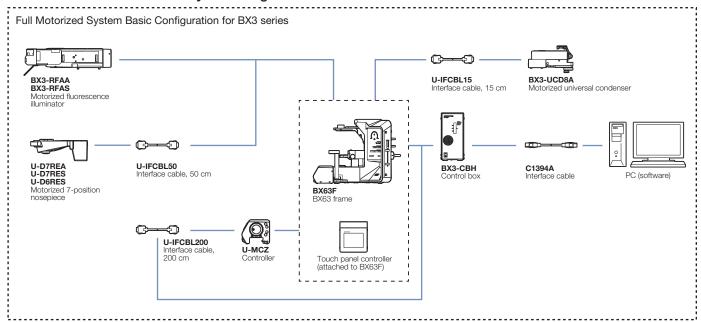


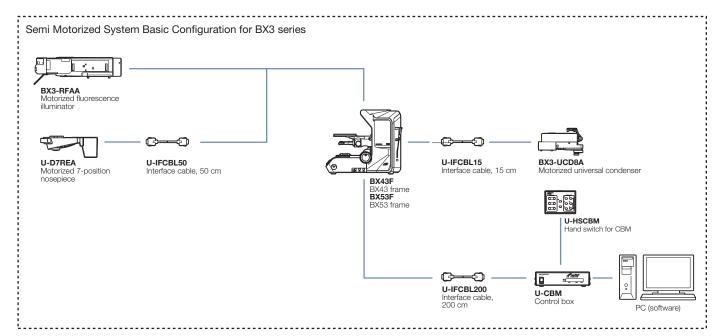
^{*1} Slight vignetting may occur in combination with an additional intermediate attachment or observation method. *2 Require an additional intermediate attachment or fluorescence illuminator.

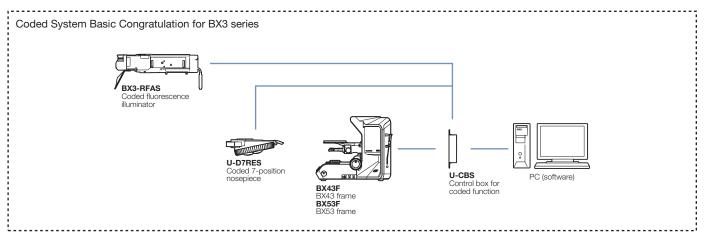
^{*3} Cannot be used with U-TTLBI. *4 Compatible with FN 22. *5 An auxiliary lens is equipped.



BX3 Series Basic Motorized System Diagram



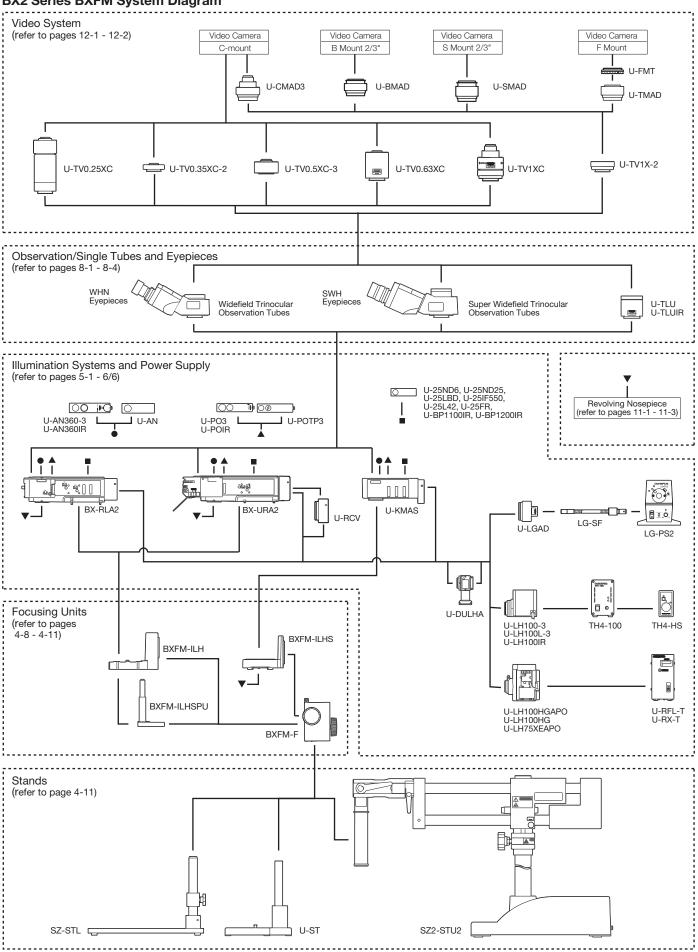




^{*}Please refer to "Section xx Motorized Unit" for each motorized unit in the detail.

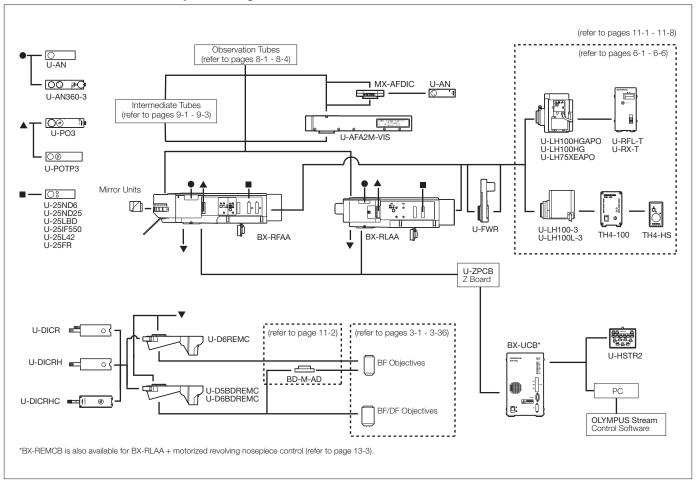
^{**}Please consult your nearest Olympus representative in you region about the detailed motorized system configuration and combination.

BX2 Series BXFM System Diagram

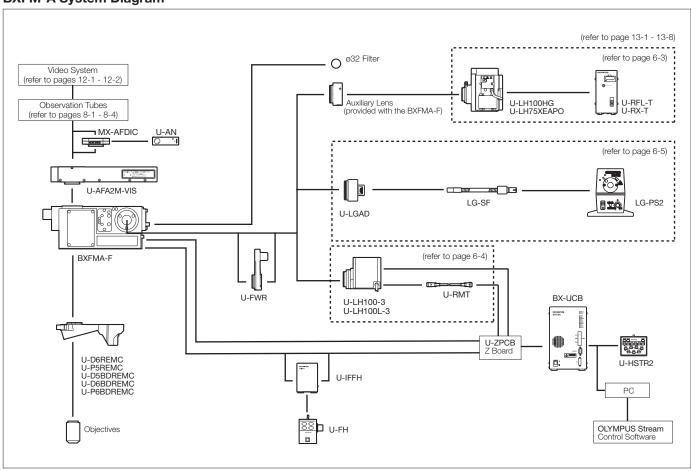


*Different types may be offered in each area.

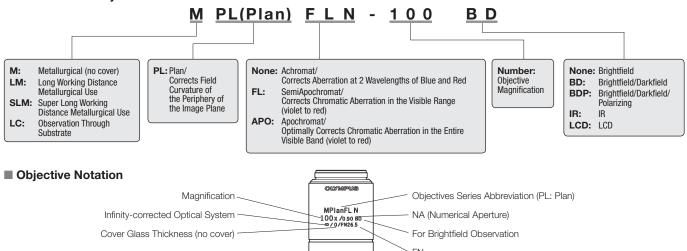
BX2 Series Motorized Unit System Diagram



BXFM-A System Diagram



■ Definition for Objective Abbreviations



■ Objective series List

Series	Magnification	BF	DF	DIC*1	POL	FL	FN	Remarks
MPLAPON	50/100	0		ΟU	0		26.5	
MPLAPON O	100	0					26.5	
MPLFLN	1.25/2.5	0					1.25X: 22/2.5X: 26.5	Use together with polarizer and
IVIPLELIN	5/10/20/40*2/50/100	0		Ou	0	○*3	26.5	analyzer recommended.
LMPLFLN	5/10/20/50/100	0		OL	0	0	26.5	
MPLN	5/10/20/50/100	0					22	
LCPLFLN-LCD	20/50/100	0		OL			26.5	for LCD
SLMPLN	20/50/100	0					26.5	
LMPLN-IR	5/10	0					22	for near-IR observation
LCPLN-IR	20/50/100	0					22	for near-IR observation
MPLFLN-BD	5/10/20/50/100/150	0	0	Ou	0	○*3	26.5	
MPLFLN-BDP	5/10/20/50/100	0	0	©υ	0	○*3	26.5	
LMPLFLN-BD	5/10/20/50/100	0		OL	0	0	26.5	
MPLN-BD	5/10/20/50/100	0	0				22	
WLI100XMRTC	100X						22	Mirau objective

^{*1} DIC Prism U-DICR: UM/LM Position, U-DICRHC: LM Position Fixed, U-DICRH: UM Position Fixed. *2 40X: BF Only *3 5-20X: U Excitation Also Possible O: Responds O: Optimally Responds BF: Brightfield DF: Darkfield DIC: Differential Interference Contrast POL: Polarized light FL: Fluorescence

■ Features of Objective Series

MPLAPON series: M Plan Apochromat — P 3-2

Plan Apochromat objectives that correct chromatic aberrations at optimal level among Olympus objectives. Olympus guarantees* optical performance (wavefront aberration) with a Strehl ratio** of 95% or better. They are also designed for use with Olympus' U-AFA2M active AF unit.

MPLAPON100X0: M Plan Apochromat — P 3-2

This is a Plan Apochromat objective of the oil-immersion type*** that features a numerical aperture of 1.4. It provides excellent chromatic aberration correction and a high resolving power.

MPLFLN series: M Plan SemiApochromat — P 3-3

Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. The lineup consists of 8 objectives ranging from 1.25X to 100X, and provides a W.D. of 1 mm or longer (except 40X). Since the exit pupil position of the 5X-100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification (40X is not applicable to DIC observation). For very low magnifications (1.25X, 2.5X), use together with analyzer and polarizer of the reflected light illuminator.

LMPLFLN series: Long WD M Plan SemiApochromat — P 3-4

Long working distance Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5X-100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

MPLN series: M Plan Achromat — P 3-5

Plan Achromat objectives providing excellent image flatness up to FN 22

■ LCPLFLN-LCD series: LCD Long WD M Plan SemiApochromat — P 3-6

Differentiated objective series for observation of LCD panels and other samples through a glass substrate. Aberration correction matched to the glass thickness is accomplished using a correction collar.

SLMPLN series: Super Long WD M Plan Achromat — P 3-7

Plan Achromat objectives with high magnification and super long working distance. Three magnifications, 20X, 50X and 100X are available. For 5X or 10X objectives, select from the LMPLELN series

■ LMPLN-IR series: IR Long WD M Plan Achromat — P 3-8

Objective series exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers.

● LCPLN-IR series: IR Long WD M Plan Achromat — P 3-9

Exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers, LCPLN-IR series has correction collar for aberration dependent on thickness of silicon or glass substrate.

● MPLFLN-BD series: M Plan SemiApochromat BD — P 3-10

Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. The series provides a W.D. of 1 mm or longer. Since the exit pupil position of the 5X-150X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

MPLFLN-BDP series: M Plan SemiApochromat BDP — P 3-11

Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. The series provides a W.D. of 1 mm or longer. Since the exit pupil position of the 5X-100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification. The BDP series optimizing brightfield/darkfield and polarized light characteristics is appropriate for Nomarski DIC and polarized light observations.

■ LMPLFLN-BD series: Long WD M Plan SemiApochromat BD — P 3-12

Long working distance Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5X-100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

● MPLN-BD series: M Plan Achromat BD — P 3-13

Plan Achromat objectives providing excellent image flatness up to FN 22

WLI100XMRTC series: White Light Interferometry Objective — P 3-14

This objective is designed for the Mirau style of white light interferometers and maintains a high level of temperature tolerance. The optimized NA of 0.8 provides improved light gathering, with a working distance of 0.7 mm.

- *Definition of guaranteed values: Measurements assessed with Olympus' Interferometer for Transmitted Wavefront Measurement under specified conditions (measurement: temp. 23°C±1°C; assessment: measurement within the 97% range of the pupil dia.).
- **Strehl ratio: Indicates in percent (%) the ratio of the proportion of light that an actual optical system can concentrate with respect to the proportion of light concentrated in the image plane (central intensity) by an ideal, aberration-free optical system, with the latter serving as 100%. A higher percentage indicates a higher quality optical system.
- ***Specified oil: IMMOIL-F30CC



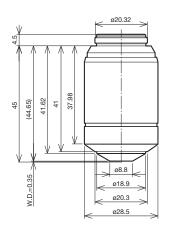
M Plan Apochromat

MPLAPON series

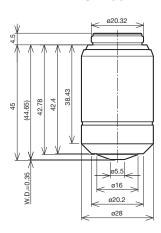


Plan Apochromat objectives that correct chromatic aberrations at optimal level among Olympus objectives. Olympus guarantees* optical performance (wavefront aberration) with a Strehl ratio** of 95% or better. They are also designed for use with Olympus' U-AFA2M active AF unit.

MPLAPON50X



MPLAPON100X



- * Definition of guaranteed values: Measurements assessed with Olympus' Interferometer for Transmitted Wavefront Measurement under specified conditions (measurement: temp. 23°C±1°C; assessment: measurement within the 97% range of the pupil dia.).
- ** Strehl ratio: Indicates in percent (%) the ratio of the proportion of light that an actual optical system can concentrate with respect to the proportion of light concentrated in the image plane (central intensity) by an ideal, aberration-free optical system, with the latter serving as 100%. A higher percentage indicates a higher quality optical system.

Unit: mm

	UIS	2 Objectives			Widefield Eyepiece Super Widefield Eyepiec WHN10X FN 22 SWH10X FN 26.5					
Objective	NA	W.D.	Focal Distance	Weight	Total	Practical Field	Depth of	Total	Practical Field	Depth of
(magnification)	INA	(mm)	f (mm)	(g)	Magnifications	of View (mm)	Focus (µm)	Magnifications	of View (mm)	Focus (µm)
MPLAPON50X	0.95	0.35	3.6	139	500	0.44	1	500	0.53	1
MPLAPON100X	0.95	0.35	1.8	125	1000	0.22	0.67	1000	0.27	0.7

Screw: W20.32 × 0.706 (0.8" × 1/36")

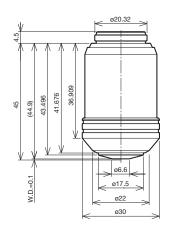
M Plan Apochromat

MPLAPON100XO



This is a Plan Apochromat objective of the oil-immersion type*** that features a numerical aperture of 1.4. It provides excellent chromatic aberration correction and a high resolving power.

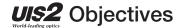
MPLAPON100XO



*** Specified Oil: IMMOIL-F30CC

Unit: mm

	UIS	2 Objectives			Widefield Eyepiece WHN10X FN 22			Super Widefield Eyepiece SWH10X FN 26.5		
Objective (magnification)	NA	W.D. (mm)	Focal Distance f (mm)		Total Magnifications	Practical Field		Total Magnifications	Practical Field	Depth of Focus (um)
MPLAPON100XO	1.4	0.1	1.8	158	1000	0.22	0.59	1000	0.27	0.59

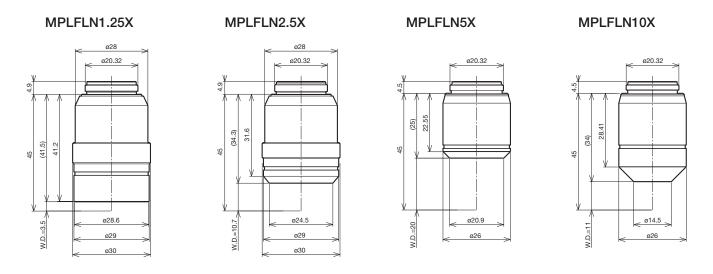


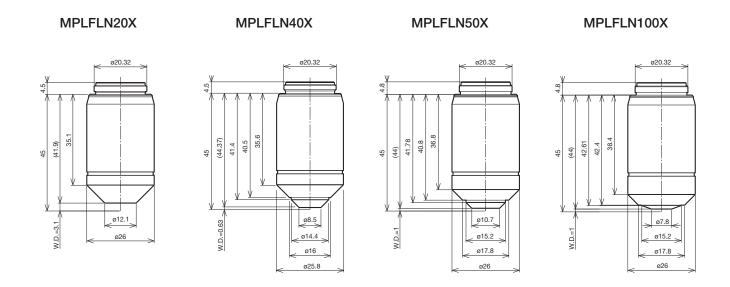
M Plan SemiApochromat

MPLFLN series



Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. The lineup consists of 8 objectives ranging from 1.25X to 100X, and provides a W.D. of 1 mm or longer (except 40X). Since the exit pupil position of the 5X–100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification (40X is not applicable to DIC observation). For very low magnifications (1.25X, 2.5X), use together with analyzer and polarizer of the reflected light illuminator.





Unit: mm

	UIS	2 Objectives			Widefield Eyepiece WHN10X FN 22			Super Widefield Eyepiece SWH10X FN 26.5		
Objective	NA	W.D.	Focal Distance	Weight	Total	Practical Field	Depth of	Total	Practical Field	Depth of
(magnification)	INA	(mm)	f (mm)	(g)	Magnifications	of View (mm)	Focus (µm)	Magnifications	of View (mm)	Focus (µm)
MPLFLN1.25X	0.04	3.5	145	122	12.5	17.6	870	_	_	_
MPLFLN2.5X	0.08	10.7	72	106	25	8.8	220	25	10.6	220
MPLFLN5X	0.15	20	36	51.5	50	4.4	59	50	5.3	59
MPLFLN10X	0.3	11	18	68.1	100	2.2	15	100	2.7	15
MPLFLN20X	0.45	3.1	9	70.4	200	1.1	5.2	200	1.3	5.1
MPLFLN40X	0.75	0.63	4.5	120	400	0.55	1.66	400	0.66	1.66
MPLFLN50X	0.8	1	3.6	89.9	500	0.44	1.3	500	0.53	1.3
MPLFLN100X	0.9	1	1.8	90.9	1000	0.22	0.73	1000	0.27	0.73



Long WD M Plan SemiApochromat

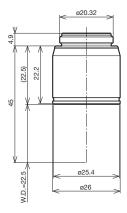
LMPLFLN series

(W.D.: Working Distance)

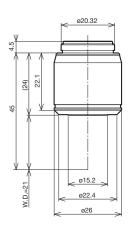


Long working distance Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5X–100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

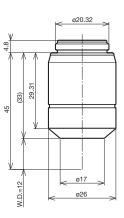
LMPLFLN5X



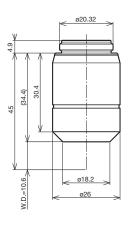
LMPLFLN10X



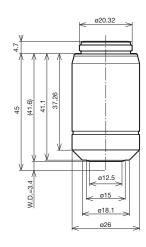
LMPLFLN20X



LMPLFLN50X



LMPLFLN100X



Unit: mm

	UIS	2 Objectives			Widefield Eyepiece WHN10X FN 22			Super Widefield Eyepiece SWH10X FN 26.5		
Objective	NA	W.D.	Focal Distance	Weight	Total	Practical Field	Depth of	Total	Practical Field	Depth of
(magnification)	INA	(mm)	f (mm)	(g)	Magnifications	of View (mm)	Focus (µm)	Magnifications	of View (mm)	Focus (µm)
LMPLFLN5X	0.13	22.5	36	50	50	4.4	70	50	5.3	70
LMPLFLN10X	0.25	21	18	54	100	2.2	18	100	2.7	18
LMPLFLN20X	0.4	12	9	73	200	1.1	6.1	200	1.3	6.1
LMPLFLN50X	0.5	10.6	3.6	77	500	0.44	2.5	500	0.53	2.5
LMPLFLN100X	0.8	3.4	1.8	94	1000	0.22	0.87	1000	0.27	0.87



M Plan Achromat

MPLN series

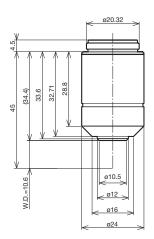


Plan Achromat objectives providing excellent image flatness up to FN 22.

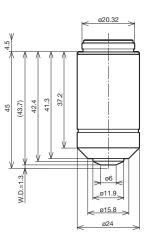
MPLN5X

23.4 (25) 45 W.D.=20

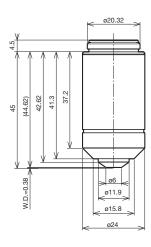
MPLN10X



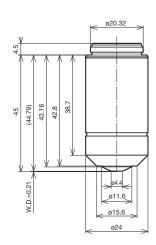
MPLN20X



MPLN50X



MPLN100X



Unit: mm

		UIS2 Objectives				Widefield Eyepiece WHN10X FN 22			
Objective (magnification)	NA	W.D. (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)		
MPLN5X	0.1	20	36	64	50	4.4	98		
MPLN10X	0.25	10.6	18	80	100	2.2	18		
MPLN20X	0.4	1.3	9	111	200	1.1	6.1		
MPLN50X	0.75	0.38	3.6	13	500	0.44	1.4		
MPLN100X	0.9	0.21	1.8	116	1000	0.22	0.73		



LCD Long WD M Plan SemiApochromat

LCPLFLN-LCD series

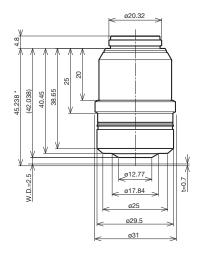


Differentiated objective series for observation of LCD panels and other samples through a glass substrate. Aberration correction matched to the glass thickness is accomplished using a correction collar.

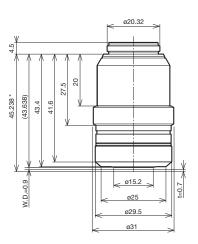
LCPLFLN20XLCD

36.55 45.238 * ø29.5

LCPLFLN50XLCD



LCPLFLN100XLCD



Unit: mm

Objective	LO	LCPLFLN20XLCD			CPLFLN50XL0	CD	LCPLFLN100XLCD			
Corresponding Glass Thickness (mm)	0–1.2				0-1.2		0-0.7			
Correction Collar Indication	0	0.7	1.2	0	0.7	1.2	0	0.5	0.7	
W.D. (mm)	8.3	7.8	7.4	3	2.5	2.2	1.2	0.98	0.9	
Correction System	Correction Collar			Correction Collar			Correction Collar			

	UIS	2 Objectives				defield Eyepie VHN10X FN 2			widefield Eye NH10X FN 26	
Objective	NA	W.D.**	Focal Distance	Weight	Total	Practical Field	Depth of	Total	Practical Field	Depth of
(magnification)	INA	(mm)	f (mm)	(g)	Magnifications	of View (mm)	Focus (µm)	Magnifications	of View (mm)	Focus (µm)
LCPLFLN20XLCD	0.45	7.8	9	146	200	1.1	5.2	200	1.3	5.2
LCPLFLN50XLCD	0.7	2.5	3.6	170	500	0.44	1.6	500	0.53	1.6
LCPLFLN100XLCD	0.85	0.9	1.8	185	1000	0.22	0.79	1000	0.27	0.79

^{*}Value at glass thickness 0.7 mm observation.

Screw: W20.32 \times 0.706 (0.8" \times 1/36") **The figure shown here is the value when the correction collar indication is 0.7.



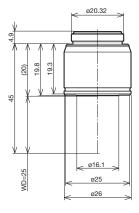
Super Long WD M Plan Achromat

SLMPLN series

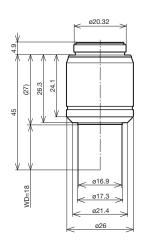


Plan Achromat objectives with high magnification and super long working distance. Three magnifications, 20X, 50X and 100X are available. For 5X or 10X objectives, select from the LMPLFLN series.

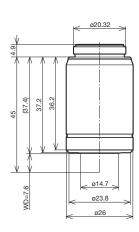
SLMPLN20X



SLMPLN50X



SLMPLN100X



Unit: mm

	UIS	2 Objectives			Widefield Eyepiece Super Widefield Eyepie WHN10X FN 22 SWH10X FN 26.5					
Objective	NA	W.D.	Focal Distance	Weight	Total	Practical Field	Depth of	Total	Practical Field	Depth of
(magnification)	INA	(mm)	f (mm)	(g)	Magnifications	of View (mm)	Focus (µm)	Magnifications	of View (mm)	Focus (µm)
SLMPLN20X	0.25	25	9	56	200	1.1	11.4	200	1.3	11.4
SLMPLN50X	0.35	18	3.6	74	500	0.44	4.2	500	0.53	4.2
SLMPLN100X	0.6	7.6	1.8	100	1000	0.22	1.3	1000	0.27	1.3

Screw: W20.32 \times 0.706 (0.8" \times 1/36")



IR Long WD M Plan Achromat

LMPLN-IR series

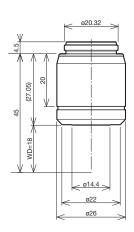


Objective series exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers.

LMPLN5XIR

650.35 620.92 620.93 620.93 620.93

LMPLN10XIR



Unit: mm

		UIS Objectives		
Objective (magnification)	NA	W.D. (mm)	Focal Distance f (mm)	Weight (g)
LMPLN5XIR	0.1	23	36	55
LMPLN10XIR	0.3	18	18	78



IR M Plan Achromat

LCPLN-IR series

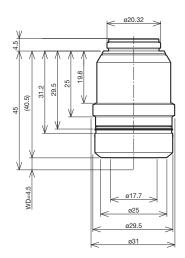


Exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers, LCPLN-IR series has correction collar for aberration dependent on thickness of silicon or glass substrate.

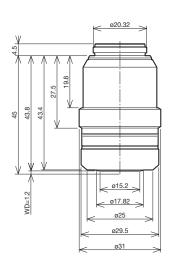
LCPLN20XIR

©20.32 ©20.32 ©3.95 ©3.95 ©4.4.64 ©14.94 ©2.5 ©2.95 ©3.95

LCPLN50XIR



LCPLN100XIR



Unit: mm

Silicon thickness correction

Objective	LCPLN20XIR				LCPLN50XIR			LCPLN100XIR			
Corresponding Silicon Thickness (mm)		0-1.2			0-1.2		0–1.0				
Correction Collar Indication	0	0.7	1.2	0	0.6 1.2		0	0.5	1		
W.D.* (mm)	8.3	8.2	8	4.5	4.3	4.1	1.2 1.1		1		
Correction System	С	orrection Coll	ar	С	orrection Coll	ar	Correction Collar		ar		

^{*}With the use of 1100 nm laser.

Silicon thickness correction

Objective	LCPLN20XLCD			LCPLN	50XLCD	LCPLN100XLCD		
Corresponding Glass Thickness (mm)		0-1.2		0-	1.2	0-0.7		
Correction Collar Indication	0	0.7	1.2	0	0 1.2		0.7	
W.D.* (mm)	8.3	7.9	7.6	4.5	3.7	1.2	0.9	
Correction System	Correction Collar		Correcti	on Collar	Correction Collar			

^{*}With the use of 1064 nm laser.

	UIS2 Objectives										
Objective (magnification)	NA*	W.D.* (mm)	Focal Distance f (mm)	Weight (g)							
LCPLN20XIR	0.45	8.3	9	149							
LCPLN50XIR	0.65	4.5	3.6	169							
LCPLN100XIR	0.85	1.2	1.8	184							

^{*}The figure shown here is the value when the correction collar indication is 0.



M Plan SemiApochromat BD

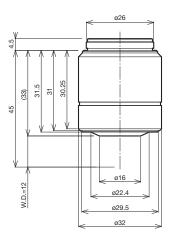
MPLFLN-BD series

(BD: Brightfield/Darkfield)

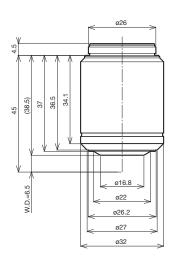


Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. The series provides a W.D. of 1 mm or longer. Since the exit pupil position of the 5X-150X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

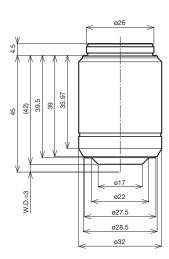
MPLFLN5XBD



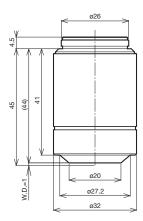
MPLFLN10XBD



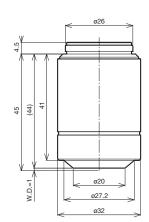
MPLFLN20XBD



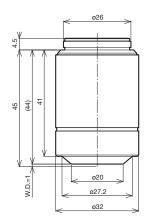
MPLFLN50XBD



MPLFLN100XBD



MPLFLN150XBD



Unit: mm

	UIS	2 Objectives			Widefield Eyepiece WHN10X FN 22				Super Widefield Eyepiece SWH10X FN 26.5		
Objective	NA	W.D.	Focal Distance	Weight	Total	Practical Field	Depth of	Total	Practical Field	Depth of	
(magnification)	(mm)		f (mm)	(g)	Magnifications	of View (mm)	Focus (µm)	Magnifications	of View (mm)	Focus (µm)	
MPLFLN5XBD	0.15	12	36	95.5	50	4.4	59	50	5.3	59	
MPLFLN10XBD	0.3	6.5	18	82.8	100	2.2	15	100	2.7	15	
MPLFLN20XBD	0.45	3	9	87.7	200	1.1	5.2	200	1.3	5.2	
MPLFLN50XBD	0.8	1	3.6	99.8	500	0.44	1.3	500	0.53	1.3	
MPLFLN100XBD	0.9	1	1.8	98.9	1000	0.22	0.73	1000	0.27	0.73	
MPLFLN150XBD	0.9	1	1.2	104.8	1500	0.15	0.6	1500	0.18	0.6	



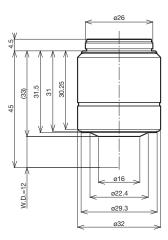
M Plan SemiApochromat BDP

MPLFLN-BDP series

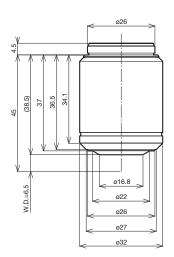


Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. The series provides a W.D. of 1 mm or longer. Since the exit pupil position of the 5X-100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification. The BDP series optimizing brightfield/darkfield and polarized light characteristics is appropriate for Nomarski DIC and polarized light observations.

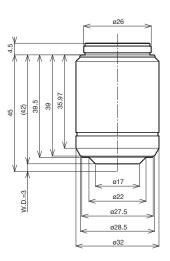
MPLFLN5XBDP



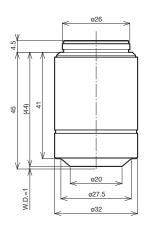
MPLFLN10XBDP



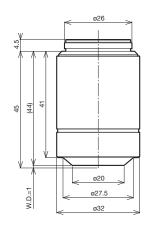
MPLFLN20XBDP



MPLFLN50XBDP



MPLFLN100XBDP



Unit: mm

	UIS	62 Objectives			Widefield Eyepiece Super Widefield Eyep WHN10X FN 22 SWH10X FN 26.5					
Objective (magnification)	NA	W.D. (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)		Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)
MPLFLN5XBDP	0.15	12	36	95.5	50	4.4	59	50	5.3	59
MPLFLN10XBDP	0.25	6.5	18	83.3	100	2.2	18	100	2.7	18
MPLFLN20XBDP	0.4	3	9	88.5	200	1.1	6.1	200	1.3	6.1
MPLFLN50XBDP	0.75	1	3.6	100.5	500	0.44	1.4	500	0.53	1.4
MPLFLN100XBDP	0.9	1	1.8	101.5	1000	0.22	0.73	1000	0.27	0.73



Long WD M Plan SemiApochromat BD

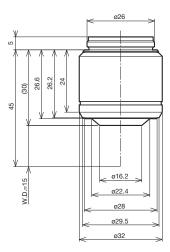
LMPLFLN-BD series

(BD: Brightfield/Darkfield)

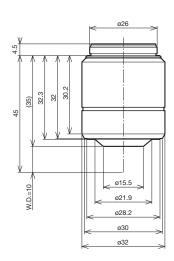


Long working distance Plan SemiApochromat objectives, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5X-100X objectives is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

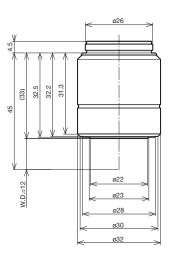
LMPLFLN5XBD



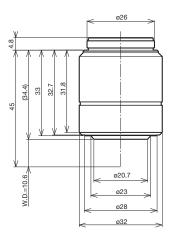
LMPLFLN10XBD



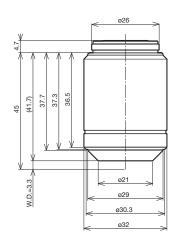
LMPLFLN20XBD



LMPLFLN50XBD



LMPLFLN100XBD



Unit: mm

	UIS	2 Objectives			Widefield Eyepiece Super Widefield Eyepiec WHN10X FN 22 SWH10X FN 26.5					
Objective	NA W.D. (mm)		Focal Distance	Weight	Total	Practical Field	Depth of	Total	Practical Field	Depth of
(magnification)			f (mm)	(g)	Magnifications	of View (mm)	Focus (µm)	Magnifications	of View (mm)	Focus (µm)
LMPLFLN5XBD	0.13	15	36	81	50	4.4	70	50	5.3	70
LMPLFLN10XBD	0.25	10	18	84	100	2.2	18	100	2.7	18
LMPLFLN20XBD	0.4	12	9	86	200	1.1	6.1	200	1.3	6.1
LMPLFLN50XBD	0.5	10.6	3.6	85	500	0.44	2.5	500	0.53	2.5
LMPLFLN100XBD	0.8	3.3	1.8	102	1000	0.22	0.87	1000	0.27	0.87



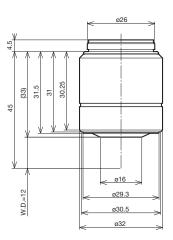
M Plan Achromat BD

MPLN-BD series

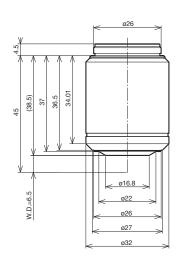


Plan Achromat objectives providing excellent image flatness up to FN 22.

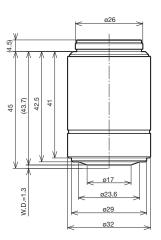
MPLN5XBD



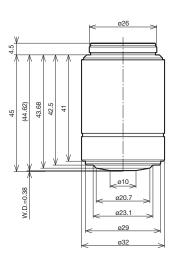
MPLN10XBD



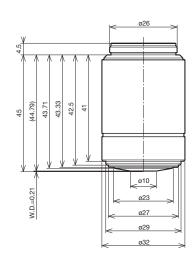
MPLN20XBD



MPLN50XBD



MPLN100XBD



Unit: mm

		UIS2 Objectives			Widefield Eyepiece WHN10X FN 22			
Objective (magnification)	NA	W.D. (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)	
MPLN5XBD	0.1	12	36	137	50	4.4	98	
MPLN10XBD	0.25	6.5	18	155	100	2.2	18	
MPLN20XBD	0.4	1.3	9	162	200	1.1	6.1	
MPLN50XBD	0.75	0.38	3.6	157	500	0.44	1.4	
MPLN100XBD	0.9	0.21	1.8	160	1000	0.22	0.73	



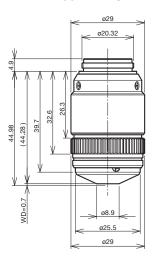
White Light Interferometry Objective

WLI100XMRTC



This objective is designed for the Mirau style of white light interferometers and maintains a high level of temperature tolerance. The optimized NA of 0.8 provides improved light gathering, with a working distance of 0.7 mm.

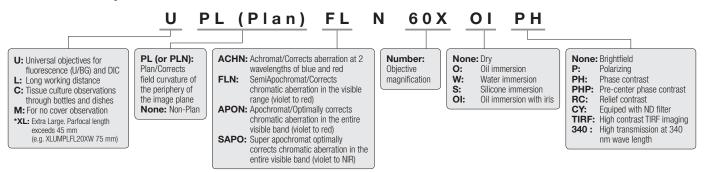
WLI100XMRTC



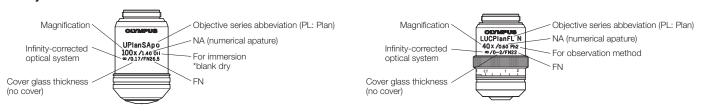
unit: mm

Objective (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
WLI100XMRTC	0.8	0.7	0	_	_	_	22.0

■ Definition for Objective Abbreviations



Objective Notation



■ Objective series List

Objective series for standard biological samples

Series	Magnification	BF	DF	DIC*	POL	FL	FN	Remarks
UPLSAPO	4X/10X/20X/20XO/40X/60XO/60XW/100XO	0	10X/20X/20XO	(except 4X)	0	0	26.5	
PLAPON	1.25X/2X/60XO	0		60XO	60XO	60XO	26.5	
UPLFLN	4X/10X/20X/40X/40XO/60X/60XOI/100XO/100XOI	0	10X/20X/40X/60XOI/100XOI	(except 4X)	0	0	26.5	
PLFLN	100X	0				0	26.5	
PLN	2X/4X/10X/20X/40X/50XOI/100XO	0	10X/20X/40X/50XOI	10X/20X/40X/50XOI		0	22	
UPLFLN-PH	4XPH/10XPH/20XPH/40XPH/60XOIPH/100XOPH	0	10XPH/20XPH/40XPH/60XOIPH			0	26.5	
PLN-PH	10XPH/20XPH/40XPH/100XOPH	0	(excpet 100XOPH)				22	
UPLFLN-P	4XP/10XP/20XP/40XP/100XOP	0	10XP/20XP/40XP	(except 4XP)	0	0	26.5	
PLN-P/ACHN-P	4XP/10XP/20XP/40XP/100XOP	0	10XP/20XP/40XP		0	0	22	
PLN-CY	2XCY/4XCY/10XCY/20XCY/(FLN) 10XCY	0					22	PLFLN10XCY FN 26.5

^{*}There objectives are suitable for standard biological samples embeded on slide glass with 0.17 mm cover slip and mainly used with upright microscopes.

Objective series for cultured samples

Series	Magnification	BF	DF	DIC	POL	FL	FN	Remarks
LUCPLFLN	20X/40X/60X	0	0	0	0	0	22	
LUCPLFLN-RC/ UCPLFLN-RC	10XRC/20XRC/40XRC	0	0			0	22	
LUCPLFLN-PH/ UCPLFLN-PH	10XPH/20XPH/40XPH/60XPH	0	0			0	22	
CPLN-PH/ LCACHN-PH	10XPH/20XPH/40XPH	0	0				22	
CPLN-RC/ LCACHN-RC	10XRC/20XRC/40XRC	0	0				22	

These objectives are suitable for cultured tissue/cell observation in dish/ bottle or micro-plate and mainly used with inverted microscopes.

Objective series for special applications

Series	Magnification	BF	DF	DIC	POL	FL	FN	Remarks
LUMPLFLN/ UMPLFLN	10XW/20XW/40XW/60XW	0	10XW/20XW	0	0	0	26.5	
XLUMPLFLN	20XW	0		0		0	22	Perocal length 75 mm
APON 340	20XW/40XO/40XW	0	20XW/40XW	0	0	0	22	
TIRF Objectives	60XO/100XHO/100XO/150XO	0		0	0	0	22	

■ Features of Objective Series (Please refer to the following page in the detail for each Objective.)

- UPLSAPO: Universal Plan Super Apochromat P 3-16
- PLAPON: Plan Apochromat P 3-18
- UPLFLN: Universal Plan Semi Apochromat/Plan Semi Apochromat P 3-19
- PI N: Plan Achromat P 3-21
- UPLFLN-PH UPlanFI-P Universal Plan Semi Apochromat for Phase Contrast P 3-23
- PLN-PH: Plan Achromat for Phase Contrast P 3-24

- UPLFLN-P: UPlanFI-P Universal Plan Semi Apochromat for Polarizing.
 P 3-25
- PLN/ACHN-P: Achromat for Polarizing. P 3-26
- PLN-CY: Plan Achromat (ND) P 3-27

- LUCPLFLN, UCPLFLN: Long Working Distance Universal Plan Semi Apochromat P 3-28
- LUCPLFLN/UCPLFLN-RC: Long Working Distance Universal Plan Semi Apochromat for Relief Contrast P 3-29
- LUCPLFLN/UCPLFLN-PH: Long Working Distanse Universal Plan Semi Apochromat for Phase Contrast P 3-30
- CPLN/LCACHN-PH: Culture Specimen Objectives for Phase Contrast P 3-31
- CPLN/LCACHN-RC: Culture Specimen Objectives for Relief Contrast P 3-32
- LUMPLFLN/UMPLFLN: No Cover Water Imarsion for Fixed Stage Upright Microscope P 3-33
- XLUMPLFLN: No Cover Water Imarsion for Fixed Stage Upright Microscope P 3-34
- APON 340: Universal Apochromat P 3-35
- TIRF Objectives P 3-36

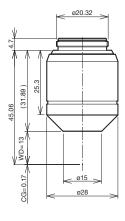
Universal Plan Super Apochromat

UPLSAPO series

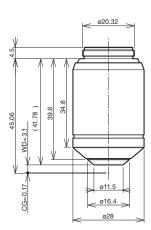


The UPLSAPO Super Apochromat objectives fully compensate for both spherical and chromatic aberrations from the UV to the nearinfrared region. The high sensitivity to fluorescence emissions allows the acquisition of sharp, clear images, without color shift, even in brightfield and Nomarski DIC observations. For quality and performance, they offer an unbeatable solution to every kind of digital imaging need.

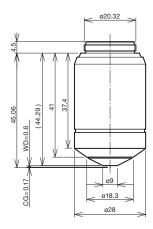
UPLSAPO4X



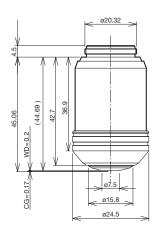
UPLSAPO10X2



UPLSAPO20X



UPLSAPO20XO



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UPLSAPO4X	0.16	13.0	_	_	_	U/BG/IR	26.5
UPLSAPO10X2	0.40	3.1	0.17	_	_	U/BG/IR	26.5
UPLSAPO20X	0.75	0.6	0.17	_	Yes	U/BG/IR	26.5
UPLSAPO20XO	0.85	0.2	_	Oil	Yes	U/BG/IR	26.5

Screw: W20.32 × 0.706 (0.8" × 1/36")

*Defined with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

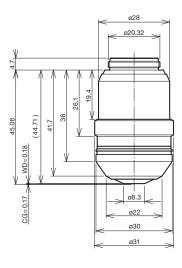
Universal Plan Super Apochromat

UPLSAPO series

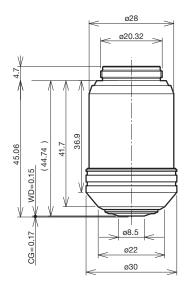


The UPLSAPO Super Apochromat objectives fully compensate for both spherical and chromatic aberrations from the UV to the nearinfrared region. The high sensitivity to fluorescence emissions allows the acquisition of sharp, clear images, without color shift, even in brightfield and Nomarski DIC observations. For quality and performance, they offer an unbeatable solution to every kind of digital imaging need.

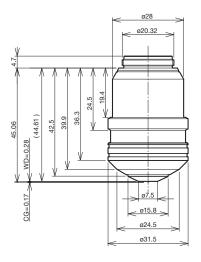
UPLSAPO40X2



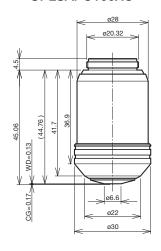
UPLSAPO60XO



UPLSAPO60XW



UPLSAPO100XO



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UPLSAPO40X2	0.95	0.18	0.11-0.23	_	Yes	U/BG/IR	26.5
UPLSAPO60XO	1.35	0.15	0.17	Oil	Yes	U/BG/IR	26.5
UPLSAPO60XW	1.20	0.28	0.13-0.21	Water	Yes	U/BG/IR	26.5
UPLSAPO100XO	1.40	0.13	0.17	Oil	Yes	U/BG/IR	26.5

Screw: W20.32 × 0.706 (0.8" × 1/36")

*Defined with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.



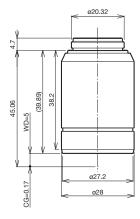
Plan Apochromat

PLAPON series

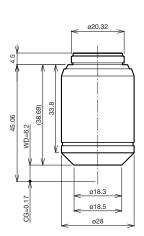


The PLAPON Apochromat objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. The high sensitivity to fluorescence emissions allows the acquisition of sharp, clear images, without color shift, even in brightfield and Nomarski DIC observations. For quality and performance, they offer an unbeatable solution to every kind of digital imaging need.

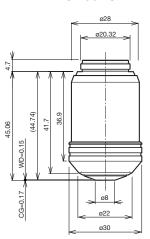
PLAPON1.25X



PLAPON2X



PLAPON60XO



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
PLAPON1.25X	0.04	5.0	_	_	_	(BG)(/IR)	26.5
PLAPON2X	0.08	6.2	_	_	_	(BG)(/IR)	26.5
PLAPON60XO	1.42	0.15	0.17	Oil	Yes	(U)/BG/IR ***	26.5

Screw: W20.32 × 0.706 (0.8" × 1/36")

*Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

***IR excitation might cause out of focus slightly.

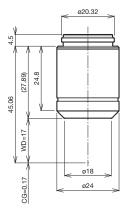
Universal Plan Semi Apochromat/Plan Semi Apochromat

UPLFLN, PLFLN series

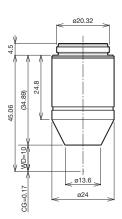


The UPLFLN and PLFLN objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. With their high S/N ratio, high resolution and contrast imaging, they are especially effective in brightfield and Nomarski DIC observations. For quality and performance, they offer an unbeatable solution to every kind of digital imaging need.

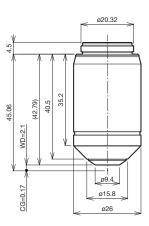
UPLFLN4X



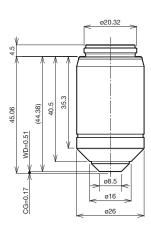
UPLFLN10X2



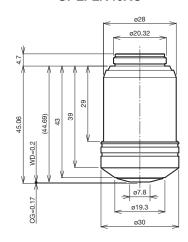
UPLFLN20X



UPLFLN40X



UPLFLN40XO



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UPLFLN4X	0.13	17	_	_	_	(U)(/BG)(/IR)	26.5
UPLFLN10X2	0.30	10	_	_	_	U/BG/IR ***	26.5
UPLFLN20X	0.50	2.1	0.17	_	Yes	U/BG/IR ***	26.5
UPLFLN40X	0.75	0.51	0.17	_	Yes	U/BG/IR ***	26.5
UPLFLN40XO	1.30	0.2	0.17	Oil	Yes	U/BG/IR ***	26.5

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

^{***}IR excitation might cause out of focus slightly.

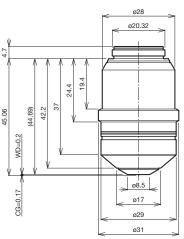
Universal Plan Semi Apochromat/Plan Semi Apochromat

UPLFLN, PLFLN series

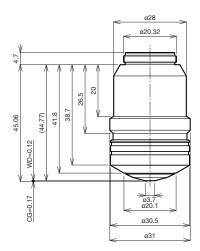


The UPLFLN and PLFLN objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. With their high S/N ratio, high resolution and contrast imaging, they are especially effective in brightfield and Nomarski DIC observations. For quality and performance, they offer an unbeatable solution to every kind of digital imaging need.

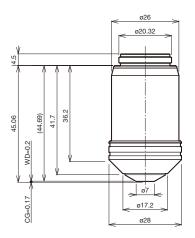
UPLFLN60X



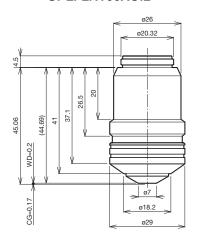
UPLFLN60XOI



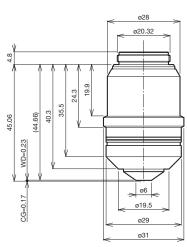
UPLFLN100XO2



UPLFLN100XOI2



PLFLN100X



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UPLFLN60X	0.90	0.2	0.11-0.23	_	Yes	U/BG/IR ***	26.5
UPLFLN60XOI	1.25-0.65	0.12	0.17	Oil	Yes	U/BG/IR ***	26.5
UPLFLN100XO2	1.30	0.2	0.17	Oil	Yes	U/BG/IR ***	26.5
UPLFLN100XOI2	1.3-0.6	0.2	0.17	Oil	Yes	U/BG/IR ***	26.5
PLFLN100X	0.95	0.2	0.14-0.2	_	Yes	BG	26.5

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

^{***}IR excitation might cause out of focus slightly.



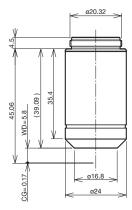
Plan Achromat

PLN series

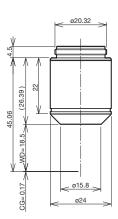


The PLN standard objectives provide excellent field flatness with fluorescence, darkfield and brightfield observation in transmitted light. These objectives are suited to clinical laboratory and examination work.

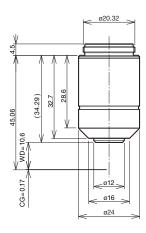
PLN2X



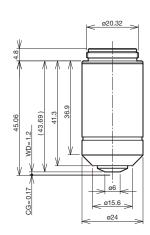
PLN4X



PLN10X



PLN20X



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
PLN2X	0.06	5.8	_	_	_	(BG)	22.0
PLN4X	0.10	18.5	_	_	_	(BG)	22.0
PLN10X	0.25	10.6	_	_	_	(BG)	22.0
PLN20X	0.40	1.2	0.17	_	Yes	(BG)	22.0

Screw: W20.32 \times 0.706 (0.8" \times 1/36") *Defined with cover glass thickness shown as "CG" in the above drawings. **U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.



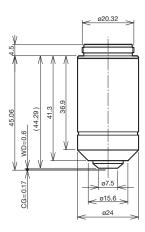
Plan Achromat

PLN series

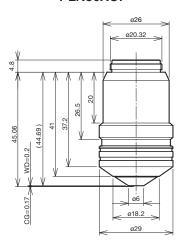


The PLN standard objectives provide excellent field flatness with fluorescence, darkfield and brightfield observation in transmitted light. These objectives are suited to clinical laboratory and examination work.

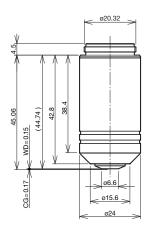
PLN40X



PLN50XOI



PLN100XO



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
PLN40X	0.65	0.6	0.17	_	Yes	(BG)	22.0
PLN50XOI	0.9-0.5	0.2	_	Oil	Yes	(BG)	22.0
PLN100XO	1.25	0.15	_	Oil	Yes	(BG)	22.0

Screw: W20.32 \times 0.706 (0.8" \times 1/36") *Defined with cover glass thickness shown as "CG" in the above drawings. **U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

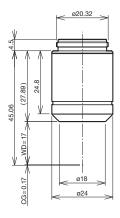
Universal Plan Semi Apochromat for Phase Contrast

UPLFLN-PH series

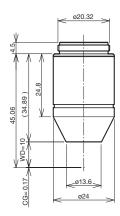


The UPLFLN-PH objectives are especially effective in phase-contrast observations with their high S/N ratio, high resolution and contrast imaging. These objectives display flat images from high transmission factors up to the near-infrared region of the spectrum.

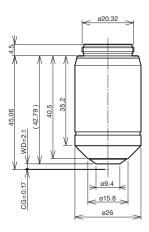
UPLFLN4XPH



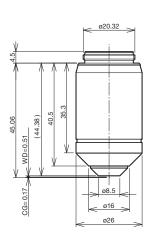
UPLFLN10X2PH



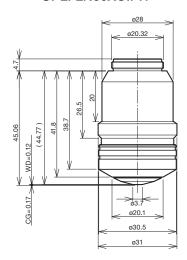
UPLFLN20XPH



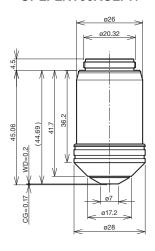
UPLFLN40XPH



UPLFLN60XOIPH



UPLFLN100XO2PH



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UPLFLN4XPH	0.13	17	_	_	_	U/BG/IR ***	26.5
UPLFLN10X2PH	0.30	10	_	_	_	U/BG/IR ***	26.5
UPLFLN20XPH	0.50	2.1	0.17	_	Yes	U/BG/IR ***	26.5
UPLFLN40XPH	0.75	0.51	0.17	_	Yes	U/BG/IR ***	26.5
UPLFLN60XOIPH	1.25-0.65	0.12	0.17	Oil	Yes	U/BG/IR ***	26.5
UPLFLN100XO2PH	1.30	0.2	0.17	Oil	Yes	U/BG/IR ***	26.5

Screw: W20.32 × 0.706 (0.8" × 1/36")

***IR excitation might cause out of focus slightly.

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.
**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

Plan Achromat for Phase Contrast

PLN-PH series

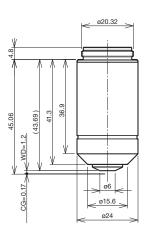


The PLN-PH standard objectives provide excellent field flatness with phase-contrast observation in transmitted light.

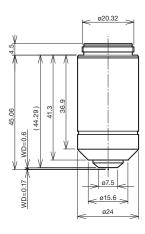
PLN10XPH

28.6 (34.29) 32.7

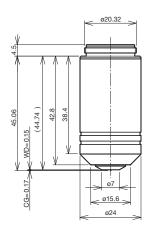
PLN20XPH



PLN40XPH



PLN100XOPH



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
PLN10XPH	0.25	10.6	_	_	_	(BG)	22.0
PLN20XPH	0.40	1.2	0.17	_	Yes	(BG)	22.0
PLN40XPH	0.65	0.6	0.17	_	Yes	(BG)	22.0
PLN100XOPH	1.25	0.15	_	Oil	Yes	(BG)	22.0

Screw: W20.32 \times 0.706 (0.8" \times 1/36") *Defined with cover glass thickness shown as "CG" in the above drawings. **U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

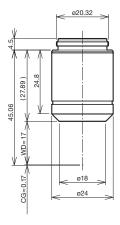
Universal Plan Semi Apochromat for Polarizing

UPLFLN-P series

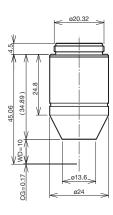


The UPLFLN-P universal objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. These objectives reduce internal strain to a minimum and are proper for polarizing, Nomarski DIC, brightfield and fluorescence microscopy.

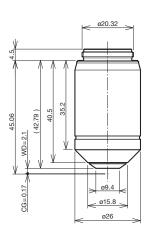
UPLFLN4XP



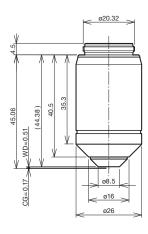
UPLFLN10XP



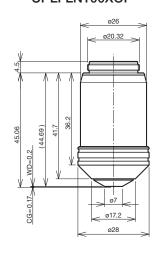
UPLFLN20XP



UPLFLN40XP



UPLFLN100XOP



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UPLFLN4XP	0.13	17	_	_	_	(U)(/BG)	26.5
UPLFLN10XP	0.30	10	_	_	_	U/BG	26.5
UPLFLN20XP	0.50	2.1	0.17	_	Yes	U/BG	26.5
UPLFLN40XP	0.75	0.51	0.17	_	Yes	U/BG	26.5
UPLFLN100XOP	1.30	0.2	0.17	Oil	Yes	U/BG	26.5

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

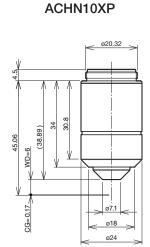
Achromat for Polarizing

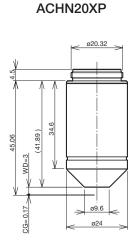
PLN-P, ACHN-P series



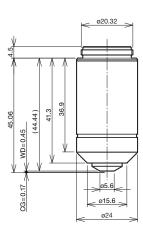
The PLN-P and ACHN-P cost-efficient objectives enable transmitted polarized light observations.

PLN4XP 9020.32 9080 9

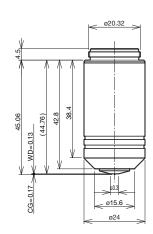




ACHN40XP



ACHN100XOP



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
PLN4XP	0.10	18.5	_ ` ′	_	_	(BG)	22.0
ACHN10XP	0.25	6	_	_	_	(BG)	22.0
ACHN20XP	0.40	3	0.17	_	_	(BG)	22.0
ACHN40XP	0.65	0.45	0.17	_	Yes	(BG)	22.0
ACHN100XOP	1.25	0.13	_	Oil	Yes	(BG)	22.0

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

Plan Achromat (ND)

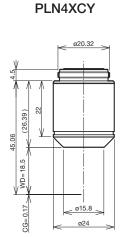
PLN-CY, PLFLN-CY series

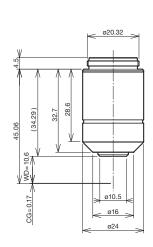


The PLN-CY and PLFLN-CY standard objectives provide excellent field flatness. These objectives, equipped with ND filters, provide the same level of brightness even if the magnification is changed, thereby removing the need for brightness adjustment.

PLN2XCY 020.32 04.66() 05.6

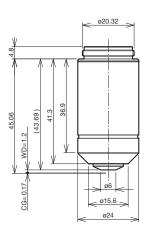
45.06



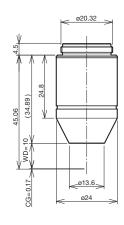


PLN10XCY

PLN20XCY



PLFLN10XCY



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
PLN2XCY	0.06	5.8	_	_	_	_	22.0
PLN4XCY	0.10	18.5	_	_	_	_	22.0
PLN10XCY	0.25	10.6	_	_	_	(BG)	22.0
PLN20XCY	0.40	1.2	0.17	_	_	(BG)	22.0
PLFLN10XCY	0.30	9.9	_	_	_	BG	26.5

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

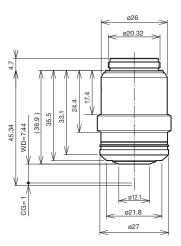
Long Working Distance Universal Plan Semi Apochromat

LUCPLFLN series

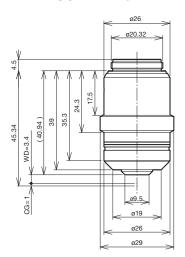


The LUCPLFLN long working distance, universal objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. These objectives are dedicated to tissue culture observations through bottles and dishes, offering high contrast and resolution in brightfield, DIC and fluorescence observations.

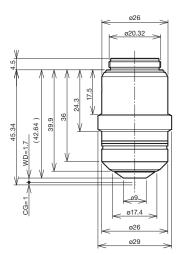
LUCPLFLN20X



LUCPLFLN40X



LUCPLFLN60X



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
LUCPLFLN20X	0.45	7.8-6.6	0-2	_	_	U/BG/IR ***	22.0
LUCPLFLN40X	0.60	4-2.7	0-2	_	_	U/BG/IR ***	22.0
LUCPLFLN60X	0.70	2.2-1.5	0.1-1.3	_	_	U/BG/IR ***	22.0

Screw: W20.32 × 0.706 (0.8" × 1/36")

*Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

***IR excitation might cause out of focus slightly.

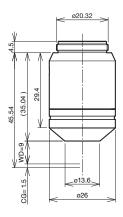
Long Working Distance Universal Plan Semi Apochromat for Relief Contrast

CPLFLN-RC, LUCPLFLN-RC series

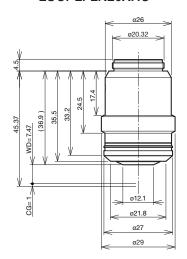


The CPLFLN-RC and LUCPLFLN-RC long working distance, universal objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. These objectives are designed for the observation of living cells, including oocytes. Plastic vessels can be used with these objectives for relief-contrast observations.

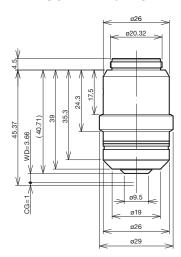
CPLFLN10XRC



LUCPLFLN20XRC



LUCPLFLN40XRC



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
CPLFLN10XRC	0.30	9 ***	_	_	_	BG	22.0
LUCPLFLN20XRC	0.45	7.8-6.6	0-2	_	_	U/BG/IR ****	22.0
LUCPLFLN40XRC	0.60	4.2-3.0	0-2	_	_	U/BG/IR ****	22.0

Screw: W20.32 × 0.706 (0.8" × 1/36")

*Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

*****IR excitation might cause out of focus slightly.

^{***}Defined by 1 mm bottom thickness of Plastic Container). 5 mm bottom thickness of Glass Heat Plate (depends on the shape of container).

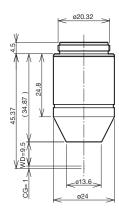
Long Working Distance Universal Plan Semi Apochromat for Phase Contrast

CPLFLN-PH, LUCPLFLN-PH series

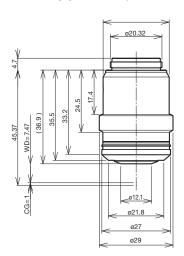


The CPLFLN-PH and LUCPLFLN-PH long working distance, universal objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. These objectives are exclusively designed for culture specimens and are optimized to produce exquisite phase-contrast images, regardless of the thickness and material of the vessel.

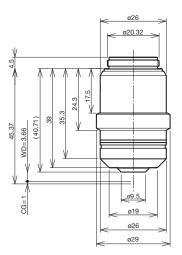
CPLFLN10XPH



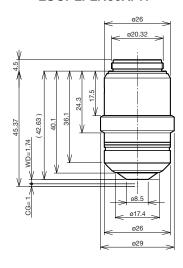
LUCPLFLN20XPH



LUCPLFLN40XPH



LUCPLFLN60XPH



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
CPLFLN10XPH	0.30	9.5 ***	1	_	_	BG	22.0
LUCPLFLN20XPH	0.45	7.8-6.6	0-2	_	_	U/BG/IR ****	22.0
LUCPLFLN40XPH	0.60	4.2-3.0	0-2	_	_	U/BG/IR ****	22.0
LUCPLFLN60XPH	0.70	2.2-1.5	0.1-1.3	_	_	U/BG/IR ****	22.0

Screw: W20.32 × 0.706 (0.8" × 1/36")

*Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

***Defined by 1 mm bottom thickness of Plastic Container.

^{****}IR excitation might cause out of focus slightly.

Culture Specimen Objectives for Phase Contrast

CPLN-PH, LCACHN-PH series

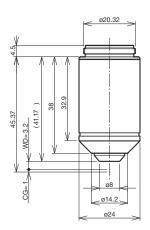


The CPLN-PH and LCACHN-PH standard objectives provide excellent field flatness with phase-contrast observation in transmitted light.

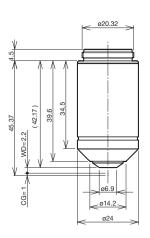
CPLN10XPH

28.5 (34.37)

LCACHN20XPH



LCACHN40XPH



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
CPLN10XPH	0.25	10 ***	_	_	_	BG	22.0
LCACHN20XPH	0.40	3.2 ***	1	_	_	BG	22.0
LCACHN40XPH	0.55	2.2 ***	1	_	_	BG	22.0

Screw: W20.32 × 0.706 (0.8" × 1/36")

*Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

***Defined by 1 mm bottom thickness of Plastic Container.

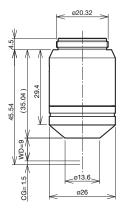
Culture Specimen Objectives for Relief Contrast

CPLN-RC, **LCACHN-RC** series

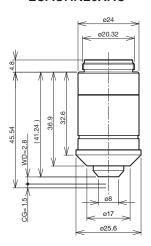


The CPLN-RC and LCACHN-RC standard objectives provide excellent field flatness with relief-contrast observation in transmitted light. These objectives are designed for the observation of living cells, including oocytes, in plastic vessels.

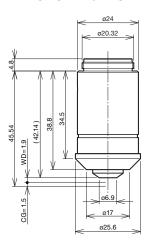
CPLN10XRC



LCACHN20XRC



LCACHN40XRC



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
CPLN10XRC	0.25	9.7 ***	_	_	_	BG	22.0
LCACHN20XRC	0.40	2.8 ***	1.5	_	_	BG	22.0
LCACHN40XRC	0.55	1.9 ***	1.5	_	_	BG	22.0

^{**}Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

***Defined by 1 mm bottom thickness of Plastic Container, 0.5 mm bottom thickness of Glass Heat Plate (depends on the shape of container).

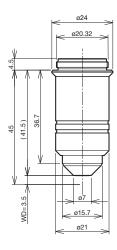
No Cover Water Immersion for Fixed Stage Upright Microscope

UMPLFLN-W, LUMPLFLN-W series

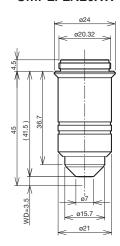


The UMPLFLN, LUMPLFLN-W and LUMFLN series of long working distance, water immersion objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. These objectives achieve exquisite DIC and fluorescence from the visible range to infrared and are ideal for fluorescence imaging of brain tissue, as well as other tissue and specimens.

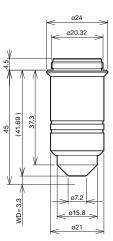
UMPLFLN10XW



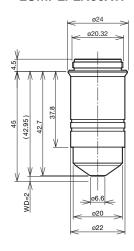
UMPLFLN20XW



LUMPLFLN40XW



LUMPLFLN60XW



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UMPLFLN10XW	0.30	3.50	0	Water	_	U/BG	26.5
UMPLFLN20XW	0.50	3.50	0	Water	_	U/BG	26.5
LUMPLFLN40XW	0.8	3	0	Water	_	U/BG	26.5
LUMPLFLN60XW	1.00	2	0	Water	_	U/BG	26.5

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.



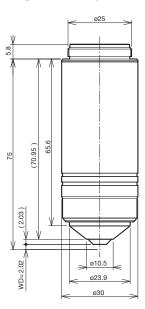
No Cover Water Immersion for Fixed Stage Upright Microscope

XLUMPLFLN20XW



The XLUMPLFLN-W high NA, long working distance objectives display flat images from high transmission factors up to the near-infrared region of the spectrum. These objectives achieve exquisite DIC and fluorescence from the visible range to infrared. These objectives allow the measurement of cell membrane electric potential as the design of the objectives provides easy access to patch clamp electrodes.

XLUMPLFLN20XW ***



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
XLUMPLFLN20XW ***	1.00	2	0	Water	_	U/BG/IR ****	22.0

Screw: W25 \times 0.75

 $[\]ensuremath{^{\star}}\xspace \text{Defined}$ with cover glass thickness shown as "CG" in the above drawings.

^{**}U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.
***Special dedicated nosepiece needed (WI-SNPXLU).
****IR excitation might cause out of focus slightly.



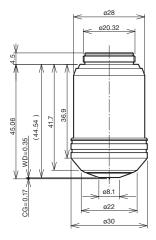
Universal Apochromat

UAPON 340 series

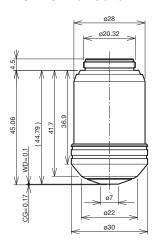


The UAPON340 objectives feature high transmission of 340nm wavelength light, providing maximum performance in fluorescence microscopes through UV excitation.

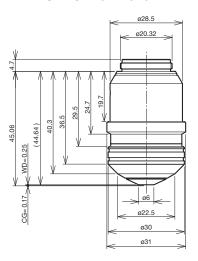
UAPON20XW340



UAPON40XO340-2



UAPON40XW340



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
UAPON20XW340	0.70	0.35	0.17	Water	Yes	U/BG	22.0
UAPON40XO340-2	1.35	0.1	0.17	Oil	Yes	U/BG	22.0
UAPON40XW340	1.15	0.25	0.13-0.25	Water	Yes	U/BG	22.0

Screw: W20.32 \times 0.706 (0.8" \times 1/36") *Defined with cover glass thickness shown as "CG" in the above drawings. **U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

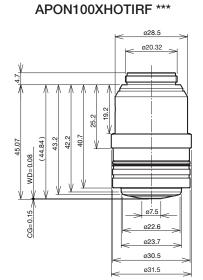
TIRF Objectives

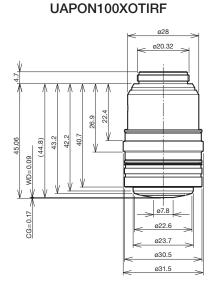
APON, UAPON series



These objectives feature the highest NA to create an evanescent wave field for high-contrast TIRF images.

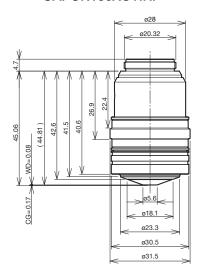
APON60XOTIRF 22.4 41.3





UAPON150XOTIRF

ø31.5



unit: mm

Objectives (Magnification)	NA	W.D. (mm) *	Cover Glass Thickness (mm)	Immersion	Spring	Fluorescence **	FN
APON60XOTIRF	1.49	0.1	0.13-0.19	Oil	_	(U)/BG	22.0
APON100XHOTIRF ***	1.70	0.08	0.15	Special Oil	_	BG	22.0
UAPON100XOTIRF	1.49	0.1	0.13-0.19	Oil	_	U/BG	22.0
UAPON150XOTIRF	1.45	0.08	0.13-0.19	Oil	_	U/BG	22.0

^{*}Defined with cover glass thickness shown as "CG" in the above drawings.

**U: UV excitation, BG: Visible Excitation, IR: Near IR. "()" indicates that fluorescence might be slightly darker.

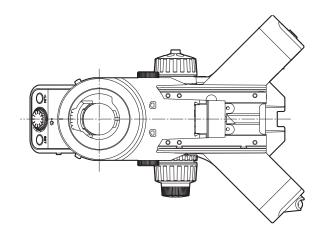
^{***}Special Dedicated Cover Glass and Immersion Oil needed.

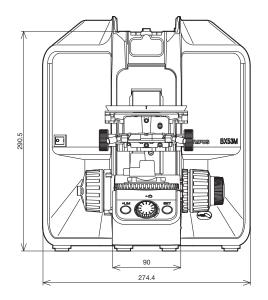
BX53M: Upright Transmitted & Reflected Light Microscope Frame

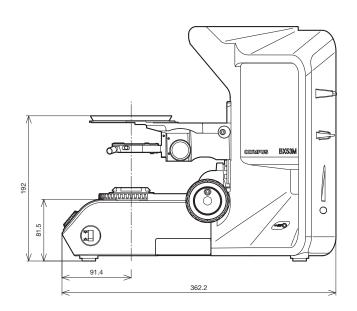
BX53MTRF-S

Designed with modularity in mind, the BX3M series provide versatility for a wide vriety of material science and industrial applications. The frames are outfitted with ESD capability to protect electronic samples.

BX53MTRF-S







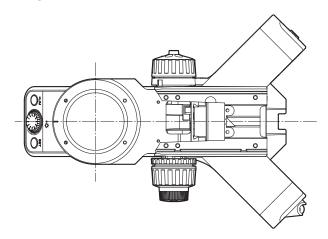
Weight: 7.6 kg Unit: mm

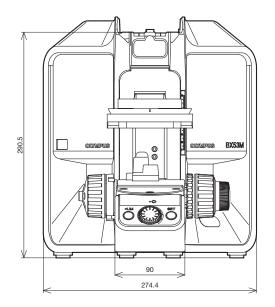
BX53M: Upright Reflected Light Microscope Frame

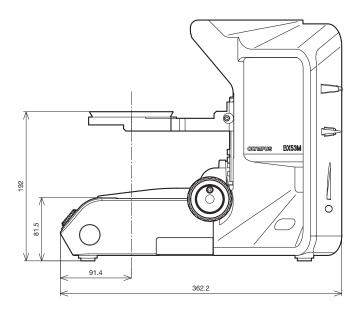
BX53MRF-S

Designed with modularity in mind, the BX3M series provide versatility for a wide vriety of material science and industrial applications. The frames are outfitted with ESD capability to protect electronic samples.

BX53MRF-S







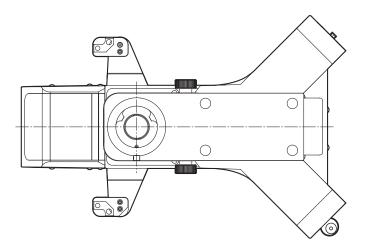
Weight: 7.4 kg Unit: mm

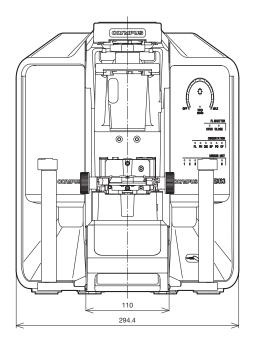
BX3: Automated Transmitted Light Microscope Frame

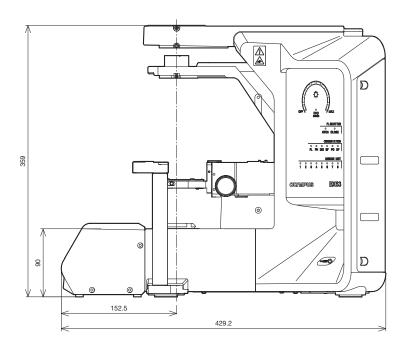
BX63F

Fully motorized system allows automation of complex multidimensional experiments, The precise motorized Z-drive, High stability due to fixed stage design.

BX63F







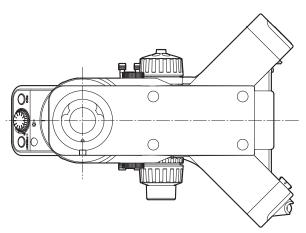
Weight: 14.1 kg Unit: mm

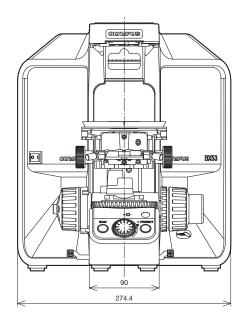
BX3: Semi-Motorized Fluorescence Transmitted Light Microscope Frame

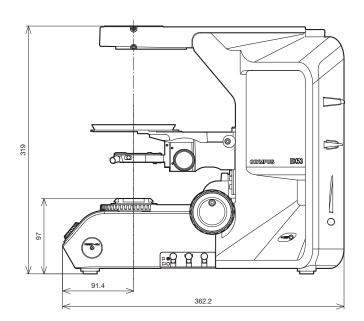
BX53F

The entire optical path of the BX53 is designed for optimal fluorescence imaging, using UIS2 components that set new standards in precision and clarity. Modular concept allows motorization of individual components.

BX53F







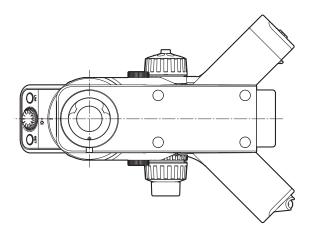
Weight: 8.3 kg Unit: mm

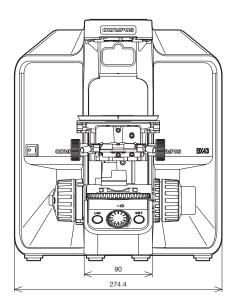
BX3: Manual System Transmitted Light Microscope Frame

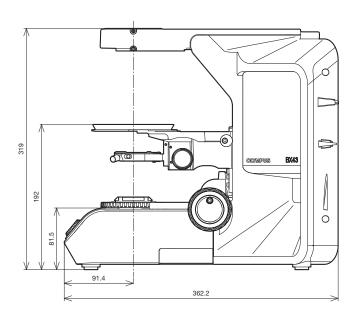
BX43F

The BX43 microscope offers a wide range of features, exquisite optical performance and is the ideal platform for digital imaging. This flexible microscope offers various contrast methods and prominent optics combined with true-color LED illumination for remarkable color rendering.

BX43F







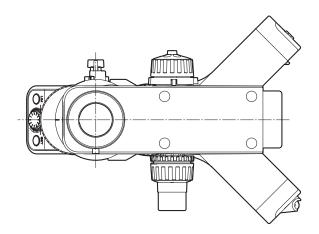
Weight: 9.1 kg Unit: mm

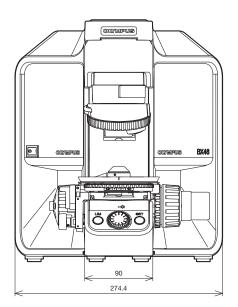
BX3: Transmitted Ergonomic Microscope Frame

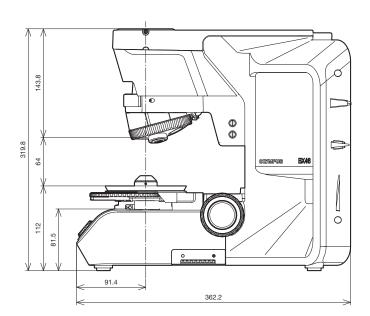
BX46F

BX46 features unrivalled ergonomic design with low-position fixed stage and nosepiece focus that increase working comfort.

BX46F





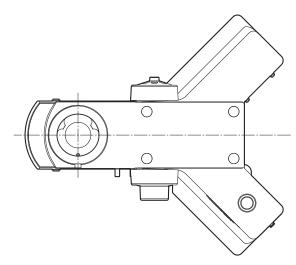


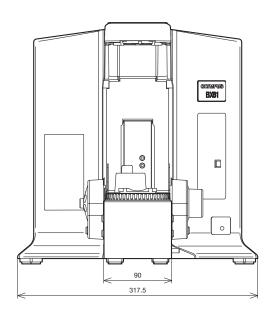
Weight: 9.8 kg Unit: mm

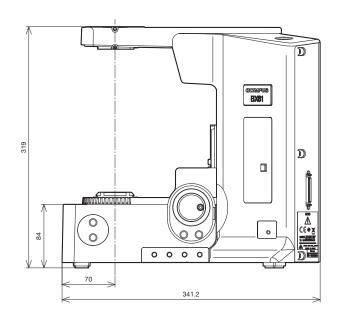
BX2: Upright Motorized Transmitted/Reflected Frame

BX61TRF

BX61TRF





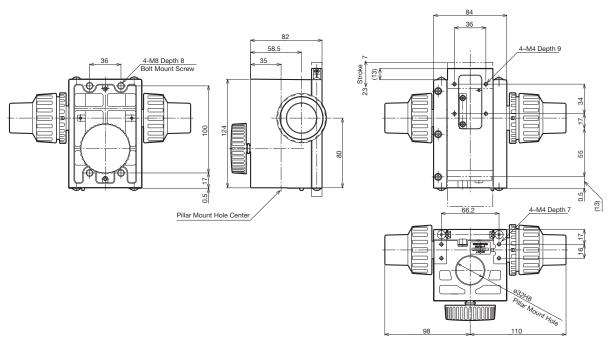


Weight: 11.4 kg Unit: mm

BXFM Frame

BXFM-F

Widely used system that allows use in combination with fiber illumination, motorized revolving nosepiece and telan lens unit. Can easily be integrated into other equipment. Attach to the equipment by rear bolt mounting screw or pillar mounting hole.

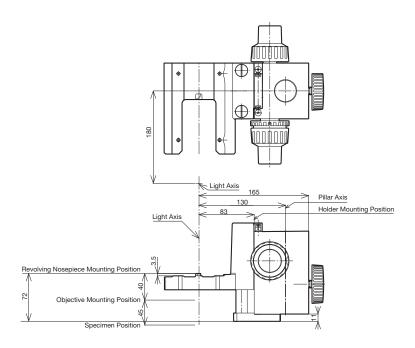


Weight: 1.9kg Unit: mm

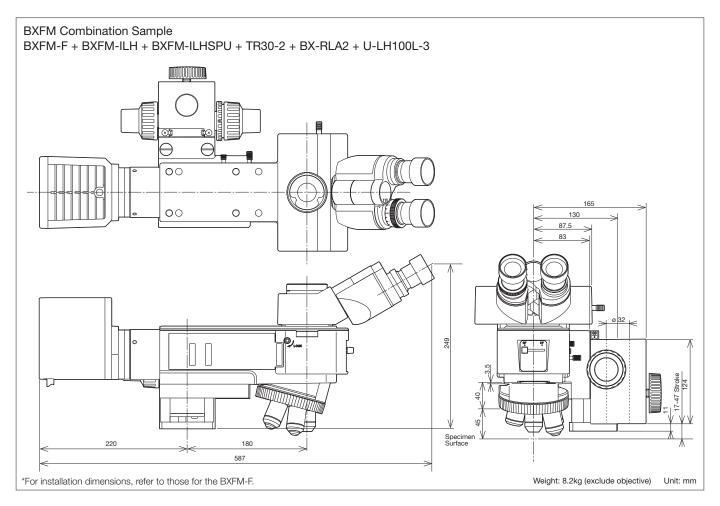
BXFM System Configuration Example1

BXFM-F + BXFM-ILH + BXFM-ILHSPU

Accommodates the reflected light brightfield/darkfield and fluorescence illuminators.



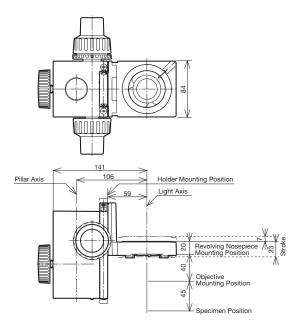
Weight: 3.2kg Unit: mm



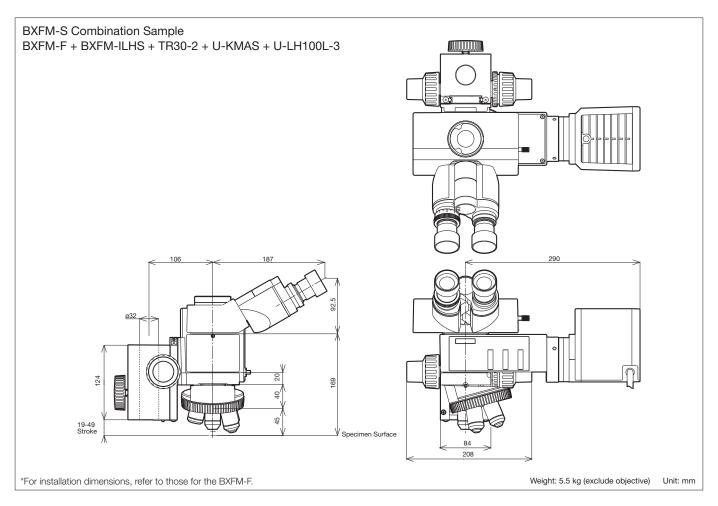
BXFM System Configuration Example2

BXFM-F + BXFM-ILHS

Compact focusing unit suitable for building into existing equipment.



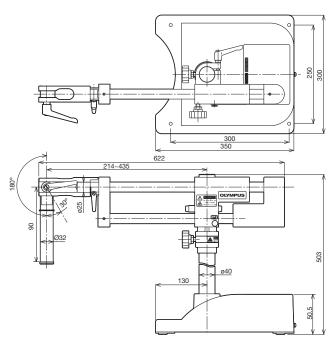
Weight: 2.4kg Unit: mm



Stands for BXFM

A wide variety of stands are available to suit different applications and purposes.

SZ2-STU2Universal Stand Type 2

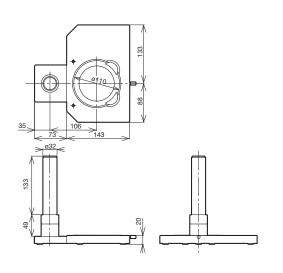


 $^{^{\}star}\text{The rotation}$ angle of the horizontal arm can restrict to 90 degrees with stopper.

Major Specifications

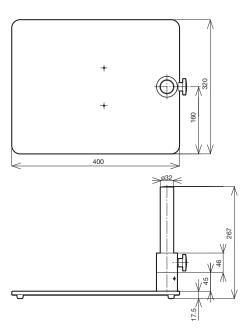
	Item	Specifications
1	Diameter of Focusing Arm or Fixing Section of Tube	ø32 mm
2	Vertical Pole Diameter	ø40 mm
3	Horizontal Poles Diameters	ø25 mm (both upper and lower poles)
4	Stroke	Horizontal: 234 mm, Vertical: 205 mm
5	Movement Range	Horizontal: 541 (435 + 106) mm max. (vertical pole — BXFM-S optical axis)
6	Maximum Specimen Weight	Forward: 10 kg (within 90-degree area) Transverse Direction: 6 kg Backward Direction: 7 kg (at maximum stroke)
7	Weight	30 kg

U-STCompact Stand



Weight: 1.8 kg

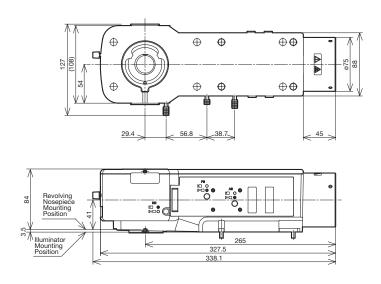
SZ-STL Large Stand



Weight: 5 kg

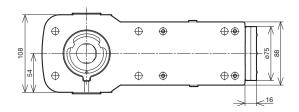
Unit: mm

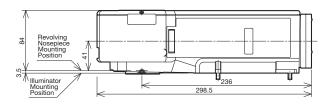
BX3M-RLA-SReflected Light Illuminator for BF/DF for BX53M



Weight: 3.0 kg

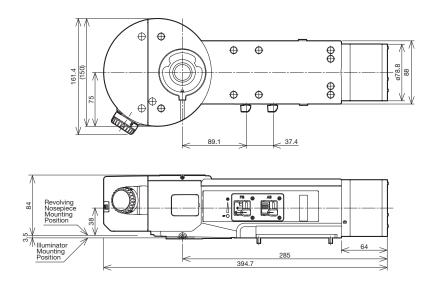
BX3M-KMA-SBF Reflected LED Light Illuminator for BX53M





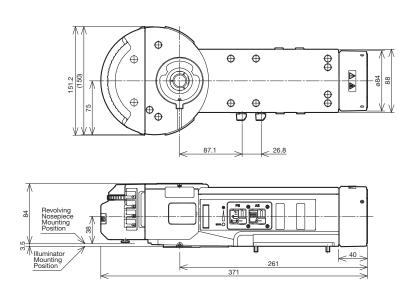
Weight: 2.4 kg Unit: mm

BX3M-RLAS-SCoded Reflected Light Illuminator for BF/DF for BX53M



Weight: 3.6 kg

BX3M-URAS-SCoded Universal Reflected Illuminator for BX53M

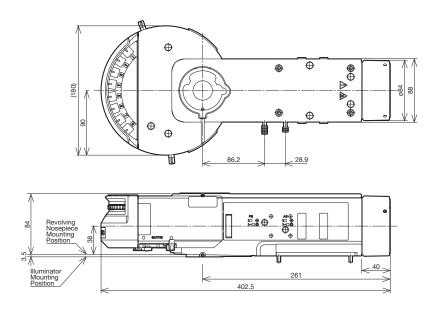


Weight: 3.2 kg Unit: mm

BX3-URA

Universal Reflected Illuminator for BX3 series

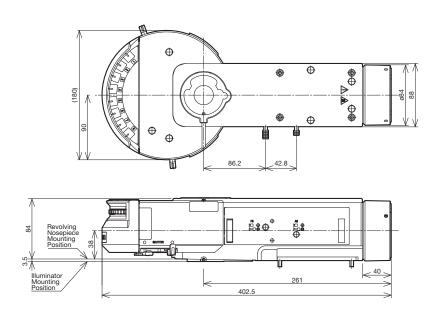
A total of eight fluorescence mirror units can be attached for comfortable multi-color fluorescence observations.



Weight: 3.8 kg

BX3-RFAS

Coded Fluorescence Illuminator for BX3 series Eight fluorescence mirror units with coded function.



Weight: 3.9 kg Unit: mm

Reflected Light Illuminator for BX2 series

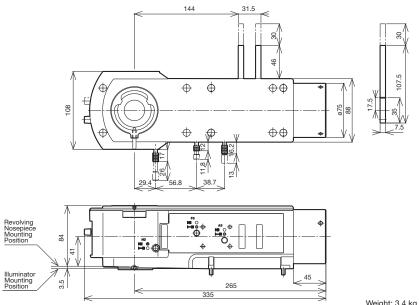
BX-RLA2

Reflected Light Illuminator for BF/DF

ND filters are linked when exchanging between brightfield and darkfield.

Accessories

Unit Name	Description	Weight (g)
U-25LBD	LBD Filter Slider	20
U-25IF550	IF550 Filter Slider	20
U-25ND6	ND Filter	20
U-25ND25	ND Filter	20
U-25FR	Frost Filter Slider	20
U-25L42	UV-cut Filter	20
U-PO3	Polarizer Slider for Reflected Light	71
U-POTP3	Polarizer Slider for Reflected Light with Tint Plate	71
U-AN360-3	360° Rotatable Analyzer Slider	79
U-AN	Analyzer Slider for Reflected Light	50
U-DICR	DIC Slider for Reflected Light	130
U-DICRH	DIC Slider for Reflected Light (Resolution type)	130
U-DICRHC	DIC Slider for Reflected Light (Contrast type)	130



Weight: 3.4 kg

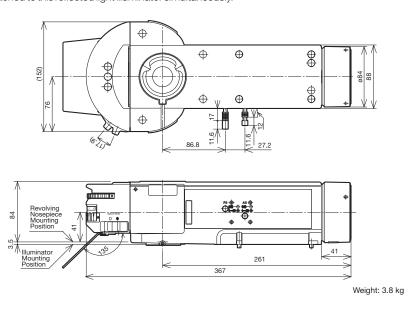
BX-URA2

Universal Reflected Light Illuminator

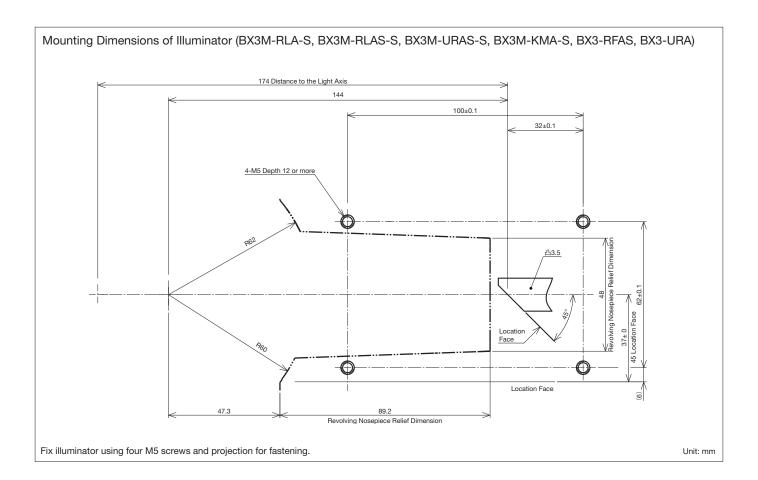
Suitable for observations ranging from brightfield to fluorescence. $Six\,mirror\,units\,can\,be\,attached\,to\,this\,reflected\,light\,illuminator\,simultaneously.$

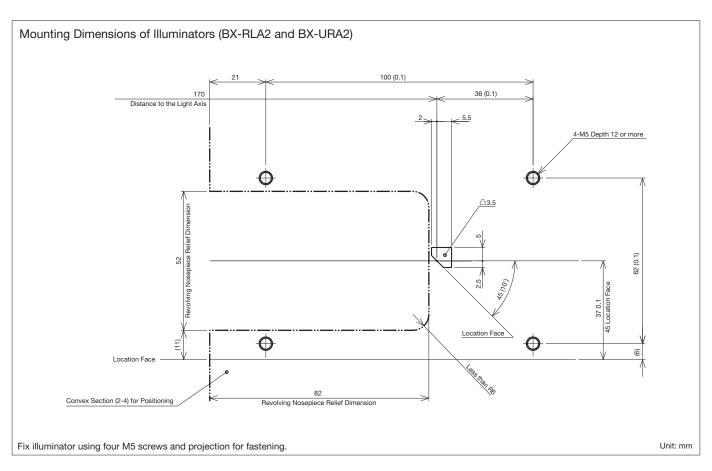
Accessories

Unit Name	Description	Weight (g)
U-25LBD	LBD Filter Slider	20
U-25IF550	IF550 Filter Slider	20
U-25ND6	ND Filter	20
U-25ND25	ND Filter	20
U-25FR	Frost Filter Slider	20
U-25L42	UV-cut Filter	20
U-PO3	Polarizer Slider for Reflected Light	71
U-POTP3	Polarizer Slider for Reflected Light with Tint Plate	71
U-AN360-3	360° Rotatable Analyzer Slider	79
U-AN	Analyzer Slider for Reflected Light	50
U-DICR	DIC Slider for Reflected Light	130
U-DICRH	DIC Slider for Reflected Light (Resolution type)	130
U-DICRHC	DIC Slider for Reflected Light (Contrast type)	130
U-MBF3	Mirror Unit for Reflected Brightfield	80
U-MDF3*	Mirror Unit for Reflected Darkfield	80
U-MDIC3	Mirror Unit for Reflected DIC	80
U-MBFL3	Mirror Unit for Reflected Brightfield, for High Intensity Light Source	80
U-MWUS3	Fluorescence Mirror Unit for Reflected (U excitation)	80
U-MWBS3	Fluorescence Mirror Unit for Reflected (B excitation)	80
U-MWGS3	Fluorescence Mirror Unit for Reflected (G excitation)	80



Illumination Units





Illumination Units

Compact Reflected Light Illuminator for BF

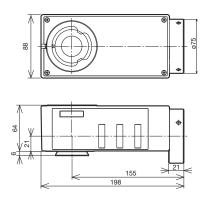
U-KMAS

Very compact reflected light illuminator with reduced depth.

U-KMAS

Accessories

Unit Name	Description	Weight (g)
U-25LBD	LBD Filter Slider	20
U-25IF550	IF550 Filter Slider	20
U-25ND6	ND Filter	20
U-25ND25	ND Filter	20
U-25FR	Frost Filter Slider	20
U-25L42	UV-cut Filter	20
U-PO3	Polarizer Slider for Reflected Light	71
U-POTP3	Polarizer Slider for Reflected Light with Tint Plate	71
U-AN360-3	360° Rotatable Analyzer Slider	79
U-AN	Analyzer Slider for Reflected Light	50
U-DICR	DIC Slider for Reflected Light	130
U-DICRH	DIC Slider for Reflected Light (Resolution type)	130
U-DICRHC	DIC Slider for Reflected Light (Contrast type)	130



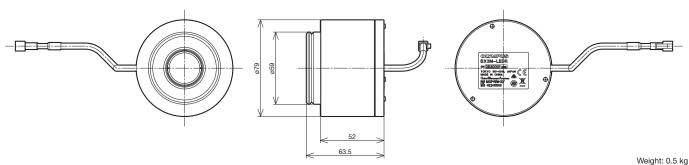
Weight: 1.2 kg

Light Source Units

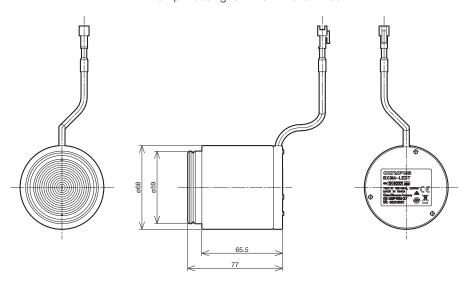
LED Lamp Housing for BX53M

The BX3M utilizes a high-intensity white LED light source for both refl ected and transmitted light. High-intensity light support various observation modes such as BF, DF, DIC and Polarizing.

BX3M-LEDRLED Lamp Housing for BX3M Reflected

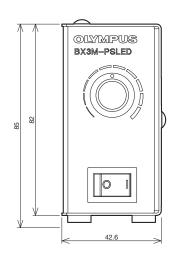


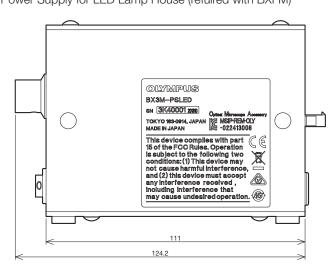
BX3M-LEDTLED Lamp Housing for BX3M Transmitted

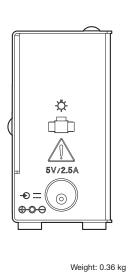


Weight: 0.5 kg

BX3M-PSLEDPower Supply for LED Lamp House (refuired with BXFM)







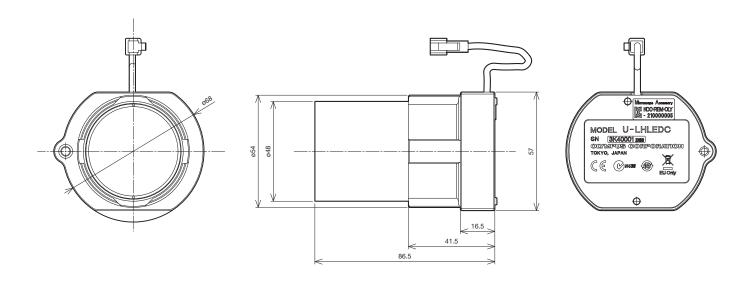
Unit: mm

Light Source Units

LED Lamp Housing for BX3 Series

The BX3M utilizes a high-intensity white LED light source for both refl ected and transmitted light. High-intensity light support various observation modes such as BF, DF, DIC and Polarizing.

U-LHLEDCLED Lamp Housing for BX3M Transmitted

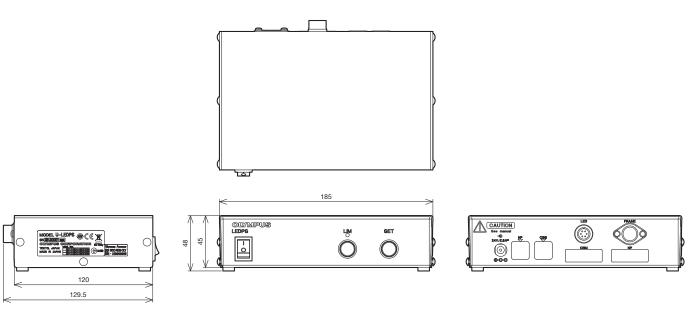


Weight: 0.5 kg

U-LEDPS

External Power Supply for U-LHLEDC

The BX3 utilizes a high color reproducible LED illumination that support a constant color temperature for consistent and support color reproduction of brightfield stains.



Weight: 0.78 kg Unit: mm

Lamp Housings

Various different lamp housings are available, for use with different light sources: choose to suit the intended purpose.

*If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand.

U-LH75XEAPO

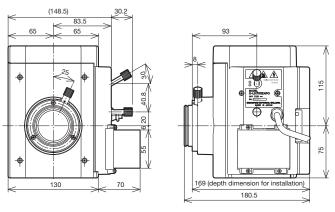
75W Xenon Apo Lamp Housing

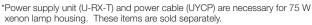
U-LH100HGAPO

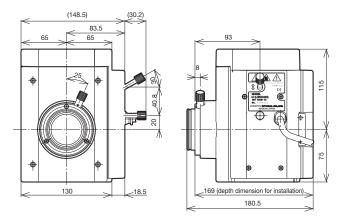
100W Mercury Apo Lamp Housing

U-LH100HG

100W Mercury Lamp Housing





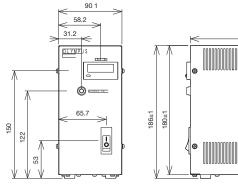


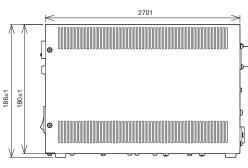
*Power supply unit (U-RFL-T) and power cable (UYCP) are necessary for 100 W mercury lamp housings. These items are sold separately.

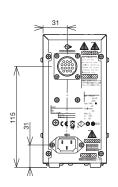
Cable Length 2,000 mm Accepted Lamp: USH-103OL Weight: 2.7 kg

Cable Length 2,000 mm Accepted Lamp: USH-103OL Weight: 2.7 kg

U-RFL-T Power Supply Unit for Mercury Lamp U-RX-T Power Supply Unit for Xenon Lamp







Weight: Approximately 3 kg

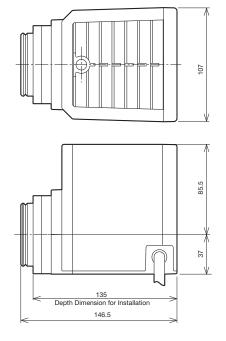
Halogen Illumination

For the 100 W halogen lamp, the external power supply TH4-100/200 with an intensity adjustment switch and an ON/OFF switch, both are located close to the operator's hand, are provided.

*If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand. Illumination devices for microscope have suggested lifetimes. Periodic inspections are required. Please visit our web site for details.

U-LH100-3/U-LH100IR/U-LH100L-3

100 W Halogen Lamp Housings



Cable Length U-LH100-3: 290 mm U-LH100IR: 290 mm U-LH100L-3: 800 mm

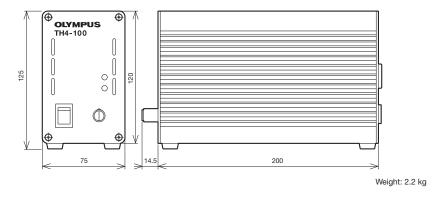
Accepted Lamp: 12V100WHAL (high intensity lamp) 12V100WHAL-L (long life lamp)

*External power supply (TH4-100 or TH4-200) and power cable (UYCP) are necessary for 100 W halogen lamp housings. These items are sold separately.

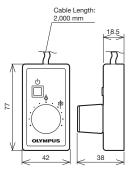
Weight: 880 g

TH4-100/200

External Power Supply



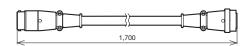
TH4-HS Hand Switch



Weight: 140 g

U-RMT

Extension Cord



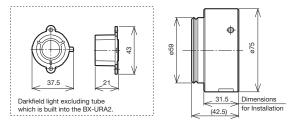
Weight: 200 g

Halogen Fiber Illumination Accessories

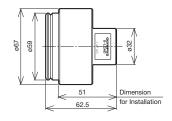
All Olympus reflected light illuminators can be used with fiber illumination.

*If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand. Illumination devices for microscope have suggested lifetimes. Periodic inspections are required. Please visit our web site for details.

U-RCVDF Converter for BX-URA2



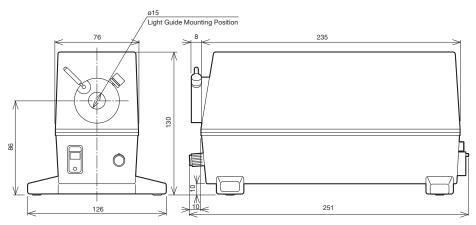
U-LGADFiber Adapter for Reflected Light Observation



Weight: 315 g

Light Guide Mount Hole ø12 Weight: 390 g

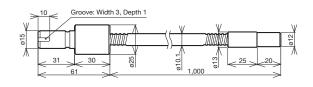
LG-PS2* Light Source



*The types of model varies by country in use.

Weight: 1.6 kg

LG-SF Light Guide



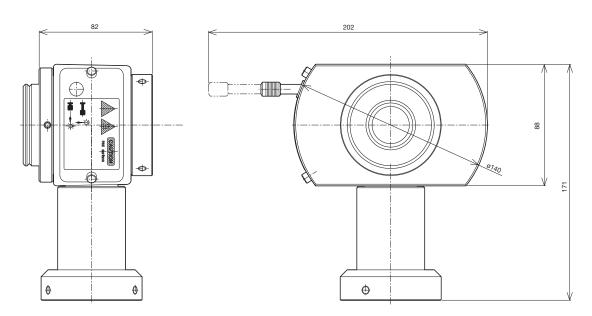
Weight: 210 g

Lamp Housing Accessory

Two lamp housings can be attached simultaneously.

*If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand.

U-DULHADouble Lamp House Adapter



Weight: 1.2 kg

Condenser Units

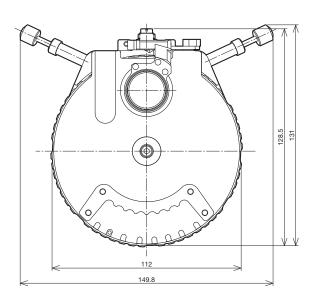
Universal Condenser

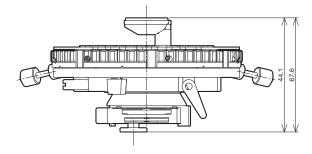
U-UCD8-2

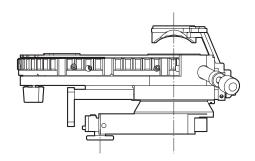
Universal condenser with 8 optical element slots.

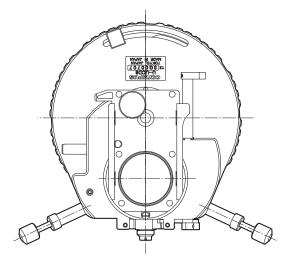
*Optical Elements are required. Please consult your nearest Olympus representative in you region about the Optical Elements Combination.

U-UCD8-2

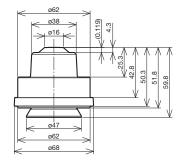




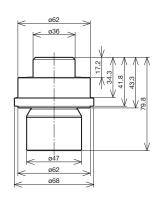




U-AC2-7Abbe Condenser

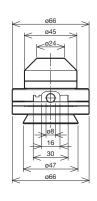


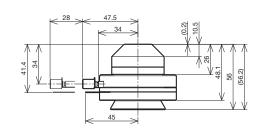
U-LWCDLong Working Distance Condenser



Weight: 174 g Weight: 380 g

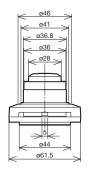
WI-OBCD
Long Working Distance Oblique Condenser

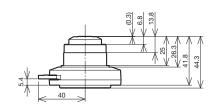




Weight: 530 g

CH3-CDBrightfield Condenser





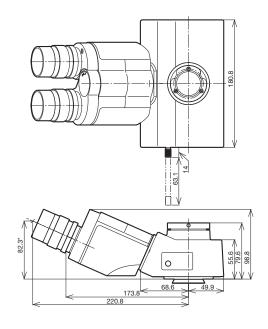
Weight: 60 g

Observation Tubes

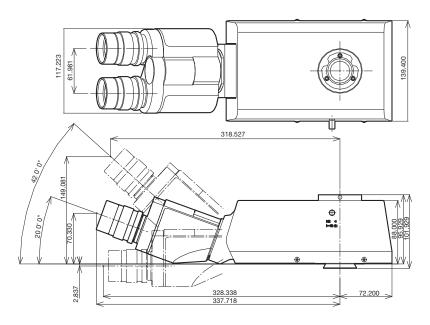
Super Widefield Trinocular Observation Tubes

Trinocular observation tubes with super widefield of view. Compatible with FN 26.5.

U-SWTR-3Super Widefield Trinocular Tube



MX-SWETTRSuper Widefield Erect Image Tilting Trinocular Tube



Name	FN	Inclination Angle (degree)	Interpupillary Distance (mm)	Light Path Selector (eyepiece/video port)	Observation Image	Weight (g)
U-SWTR-3	26.5	24	50-76	100/0, 20/80, 0/100	Inverted	2300
MX-SWETTR	26.5	0-42	50-76	100/0, 0/100	Erect	4200

^{*}Length marked with an asterisk (*) may vary according to interpupillary distance. The distance for figure shown is 62 mm.

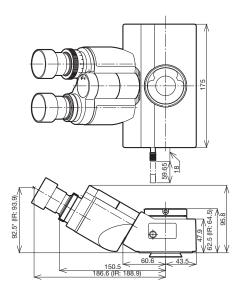
Observation Tubes

Widefield Trinocular Observation Tubes

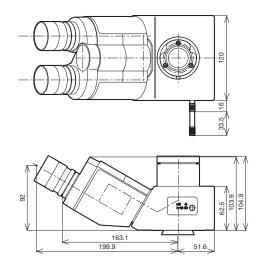
Trinocular observation tubes with widefield of view. Compatible with FN 22.

U-TR30-2 Widefield Trinocular Tube U-TR30IR

Widefield Trinocular Tube for IR



U-ETR-4Widefield Erect Image Trinocular Tube



Unit: mm

Name	FN	Inclination Angle (degree)	Interpupillary Distance (mm)	Light Path Selector (eyepiece/video port)	Observation Image	Weight (g)
U-TR30-2	22	30	50-76	100/0, 20/80, 0/100	Inverted	1600
U-TR30IR	22	30	50-76	100/0, 0/100	Inverted	1600
U-ETR-4	22	30	50-76	100/0, 0/100	Erect	1900

^{*}Length marked with an asterisk (*) may vary according to interpupillary distance. The distance for figure shown is 62 mm.

Single Port Tube with Lens

When the visual observation is not needed and only video observation is required, a single port tube with a built-in telan lens can be attached directly to the video port.

U-TLUSingle Port Tube with Lens

U-TLUIR

Single Port Tube with Lens for IR

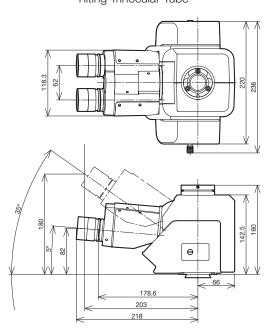


[•] For attachable video camera adapters, refer to video camera adapters system diagram page (pages 2-12 - 2-13).

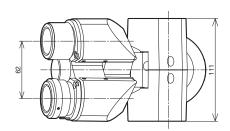
U-TTBITelescopic Tilting Binocular Tube

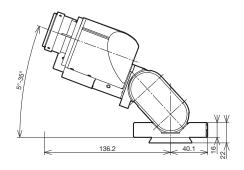
317.2 317.2 317.2 40.8 45 219.5

U-TTR-2Tilting Trinocular Tube



U-TBI-3Tilting Binocular Tube

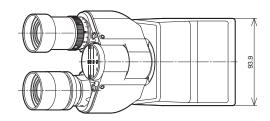


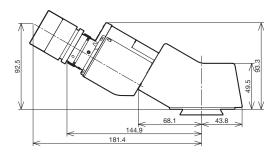


Name	FN	Inclination Angle (degree)	Interpupillary Distance (mm)	Light Path Selector (eyepiece/video port)	Observation Image	Weight (g)
U-TTBI	22	0-25	50-76	NA	Inverted	3800
U-TTR-2	22	5-35	50-76	100/0, 0/100, 50/50	Inverted	3200
U-TBI-3	22	5-35	50-76	NA	Inverted	1300

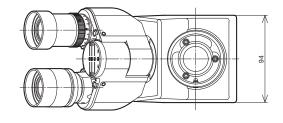
^{*}In the case of combination with CX-RFA-2, FN reduces to 18.

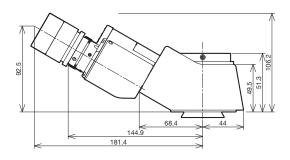
U-CBI30-2 Binocular Tube





U-CTR30-2 Trinocular Tube





Name	FN	Inclination Angle (degree)	Interpupillary Distance (mm)	Light Path Selector (eyepiece/video port)	Observation Image	Weight (g)
U-CBI30-2	20, 18(*)	30	48-75	NA	Inverted	800
U-CTR30-2	20, 18(*)	30	48-75	NA	Inverted	900

^{*}In the case of combination with CX-RFA-2, FN reduces to 18.

Intermediate Tubes & Accessories

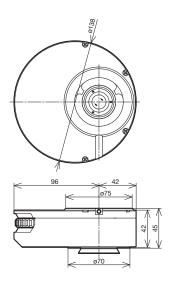
Intermediate Tubes

Various accessories for various observation need.

U-CA

Magnification Changer

Provides 1X, 1.2X, 1.6X and 2X intermediate magnifications.



Weight: 1.3 kg

U-ECA

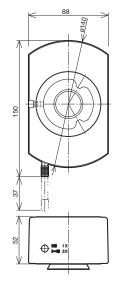
Magnification Changer 2C

Provides 1X and 2X intermediate magnifications.

U-ECA1.6X

Magnification Changer 1.6X

Provides 1X and 1.6X intermediate magnifications.

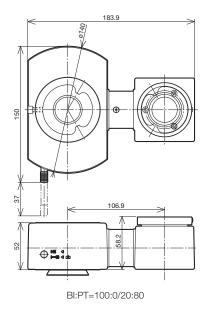


Weight: 1.3 kg

U-TRU

Trinocular Intermediate Attachment

Intermediate attachment which divides the light path, allowing attachment of both digital and video cameras.



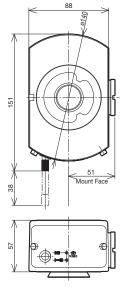
Weight: 1.3 kg

Intermediate Tubes & Accessories

Intermediate Tubes

Various accessories for various observation need.

U-DP **Dual Port** Use this intermediate tube to divide the light path.



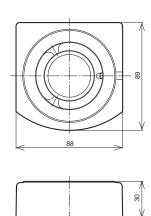
Light Path Selector by Mirror Unit

Transmitted Side Port: Side Port = 100:0

Transmitted Side Port: Side Port = 70:30 (with use of U-MBF3)

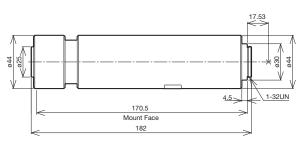
Weight: 1 kg

U-EPA2 Eyepoint Adjuster Raises eyepoint by 30 mm.



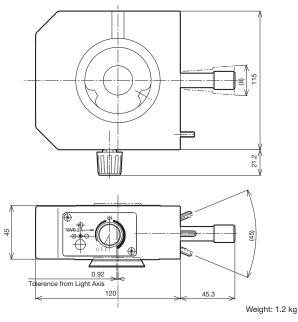
Weight: Approximately 500 g

U-DP1XC Dual Port 1X Combine with U-DP to obtain a 1X image.



Weight: 500 g

U-APT Arrow Pointer



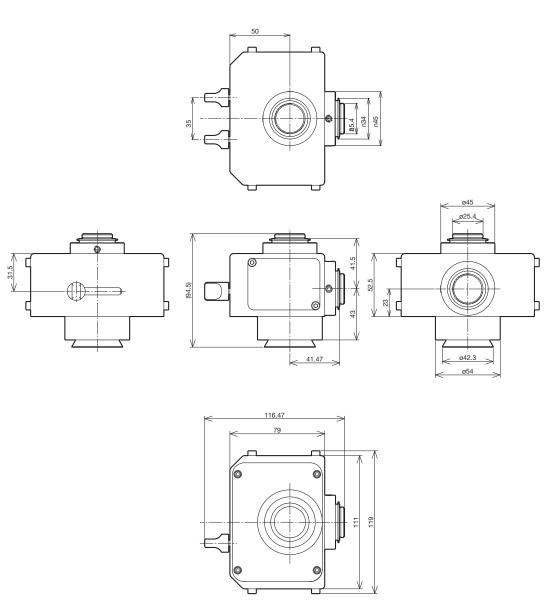
Intermediate Tubes & Accessories

Dual port tube with C mounts

U-DPCAD

Dual camera port allows the attachment of two cameras.

U-DPCAD



Weight: 0.9 kg Unit: mm

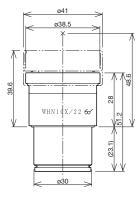
Eyepieces

Eyepieces

Eyepieces for UIS2 optical system.

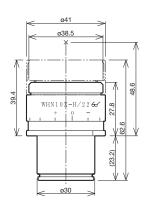
WHN10X

Widefield Eyepiece



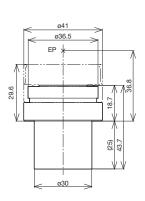
WHN10X-H CROSSWHN10X

Widefield Eyepieces



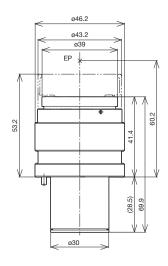
WH15X

Widefield Eyepiece



SWH10X-H MICROSWH10X CROSSSWH10X

Super Widefield Eyepieces



unit: mm

Name	FN	Diopter Adjustment Range (1/m)	Micrometer Diameter (mm)	Weight (g)	Remarks
WHN10X	22	_	24	90	
WHN10X-H	22	-8 — +5	24	170	with Adjustable Diopter
CROSSWHN10X	22	-8 - +5	_	170	with Cross Lines and Adjustable Diopter
WH15X	14	_	24	90	
SWH10X-H	26.5	-8 - +2	_	210	with Adjustable Diopter
MICROSWH10X	26.5	-8 - +2	_	210	with Micrometer and Adjustable Diopter
CROSSSWH10X	26.5	-8 - +2	_	210	with Cross Lines and Adjustable Diopter

^{*}EP=eyepoint

Revolving Nosepieces

Revolving Nosepieces for BF Objectives

Choose from following 6 types. For motorized nosepieces, refer to motorized unit page.

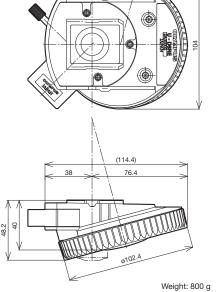
U-5RE-2

Quintuple Revolving Nosepiece for BF/DF with Slider Slot for DIC

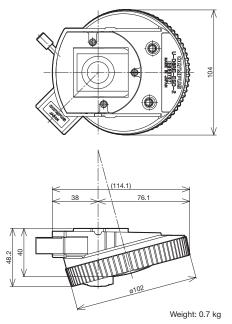
883

(87.4) 26.5 60.9 Weight: 520 g

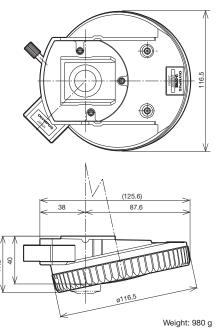
U-D6RE
Septuple Revolving Nosepiece
with Slider Slot for DIC



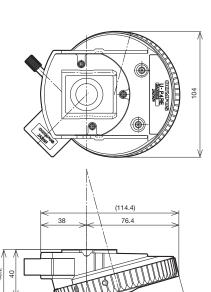
U-D6RE-ESD
Sextuple Revolving Nosepiece with
Slider Slot for DIC with ESD Treatment



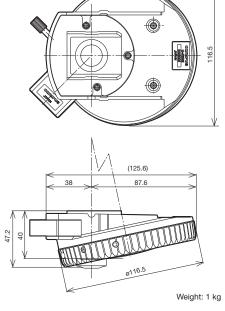
U-D7RE
Sextuple Revolving Nosepiece
with Slider Slot for DIC



U-P4RE
Centerable Quadruple Revolving
Nosepiece with Slider Slot for DIC



U-P6RECenterable Sextuple Revolving
Nosepiece with Slider Slot for DIC



Insert the DIC dummy when not using the DIC slider. unit: mi

Revolving Nosepieces

Revolving Nosepieces for BF/DF Objectives

Choose from following 3 types. Use of adapter to mount BF objectives (BD-M-AD) enables attachment of brightfield objectives. For motorized nosepieces, refer to motorized unit page.

U-5BDRE

Quintuple Revolving Nosepiece for BF/DF

U-D5BDRE

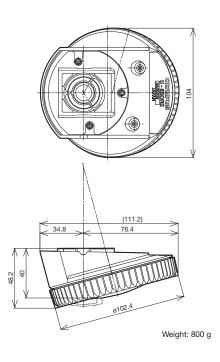
Quintuple Revolving Nosepiece for BF/DF with Slider Slot for DIC

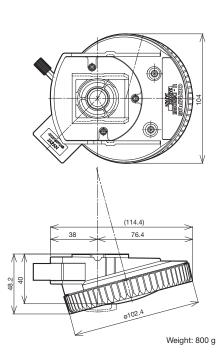
U-P5BDRE

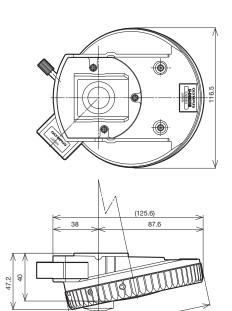
Centerable Quintuple Revolving Nosepiece with Slider Slot for DIC

U-D6BDRE

Sextuple Revolving Nosepiece for BF/DF with Slider Slot for DIC

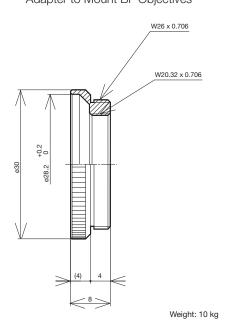






Insert the DIC dummy when not using the DIC slider.

BD-M-ADAdapter to Mount BF Objectives

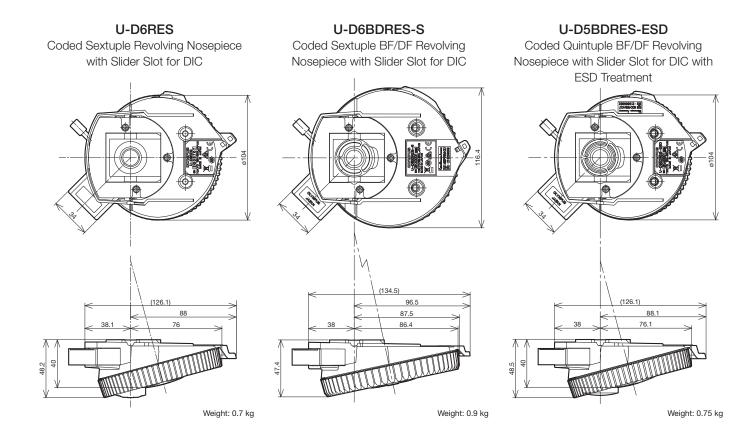


unit: mm

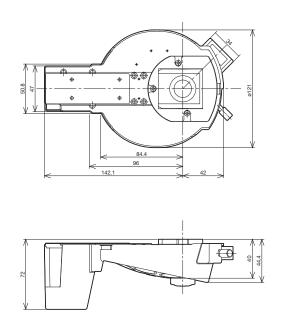
Weiaht: 1 ka

Revolving Nosepieces

Coded Sextuple Revolving Nosepiece



U-D7RESCoded Septuple Nosepiece with Slider Slot for DIC



unit: mm

Video Camera Adapters

C-mount Video Camera Ports

Allows direct attachment of a C-mount video camera. Five types are provided: 1X, 0.63X, 0.5X, 0.35X and 0.25X. All models feature a focus adjustment function.

U-TV0.25XC

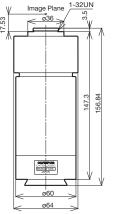
C-mount Video Port with 0.25X Lens

U-TV0.35XC-2

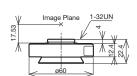
C-mount Video Port with 0.35X Lens

U-TV0.5XC-3

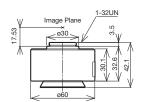
C-mount Video Port with 0.5X Lens



Weight: 1.2 kg



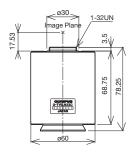
Weight: 100 g



Weight: 200 g

U-TV0.63XC

C-mount Video Port with 0.63X Lens

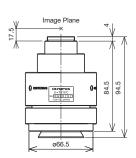


Projection Area

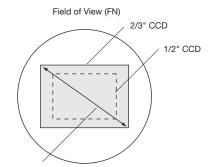
Weight: 430 g

U-TV1XC

C-mount Video Port with 1X Lens



Weight: 300 g



Video Camera Adapter	Projection	Pro	jection Area (FN)
(projection lens)	Magnifications		1/2" CCD	1/3" CCD
U-TV1X-2	1X	11	8	6
U-TV1XC	1X	11	8	6
U-TV0.63XC	0.63X	17.5	12.7	9.5
U-TV0.5XC-3	0.5X	22	16	12
U-TV0.35XC-2	0.35X	_	22	17.1
LI-TV0 25XC	0.25X	_	_	24

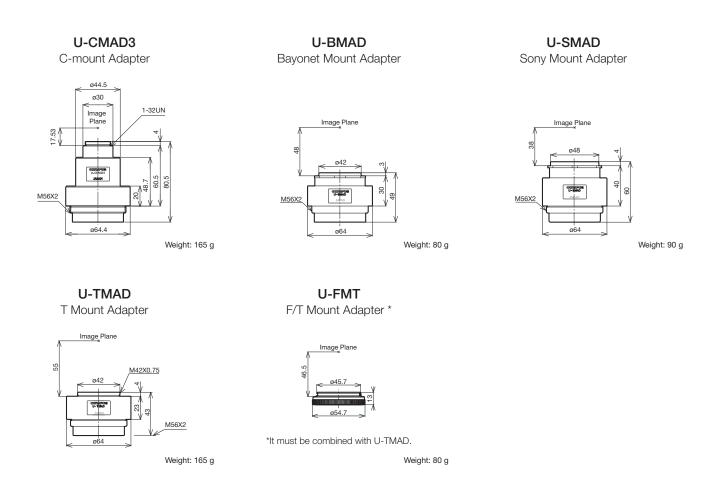
 $Practical \ Field \ of \ View \ (mm) = \frac{Projection \ Area \ (FN)}{Objective \ Magnifications}$

Focus the video camera adapter to prevent defocusing the eyepiece image and defocusing by magnification switching. Generally, the video camera adapter is focused by switching to a low magnification after focusing at a high magnification objective.

Video Camera Adapters

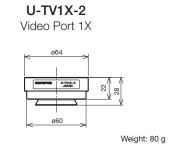
Video Camera Mount Adapters

Allows attachment to video cameras with C, Bayonet, Sony and F mounts. Use with the U-TV1X-2. Focus by amount of screwing into U-TV1X-2.



Video Camera Port

This port can be attached directly to the trinocular observation tube as well as to the single port tube with lens.

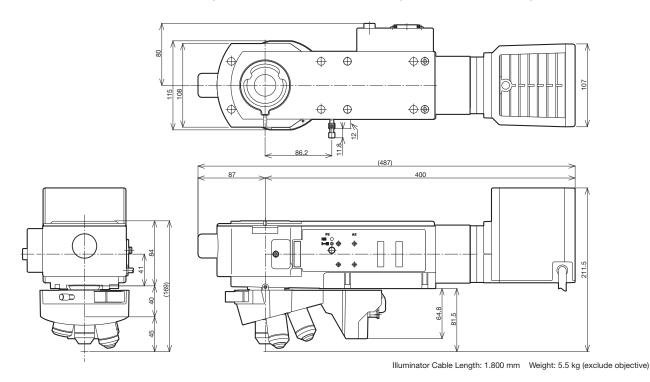


Motorized Universal Reflected Illminator for BX2 Series

Various motorized units, appropriate for automation of equipment, are available.

BX-RLAA + U-D6REMC + U-LH100-3

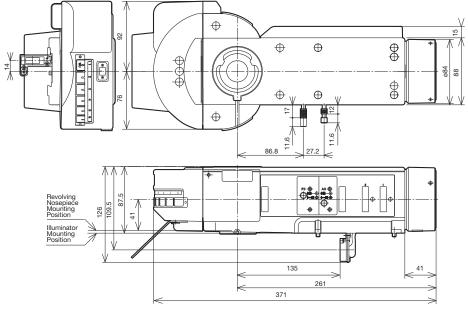
Motorized BF/DF Reflected Light Illuminator + Motorized Nomarski DIC Sextuple Revolving Nosepiece + 100 W Halogen Lamp Housing Enables motorized exchange of objectives, selection between brightfield and darkfield observations as well as aperture diaphragm closing/opening. The BX-UCB control unit has an RS232C connector, allowing control via a PC. For method of attaching illuminator, refer to Mounting Dimensions of BX-RLA2.



BX-RFAA

Motorized Universal Reflected Light Illuminator

Reflected light fluorescence illuminator with simultaneous attachment of six mirror units. Incorporates motorized mirror unit changeover and shutter.



Illuminator Cable Length: 1.800 mm Weight: 4.3 kg

Motorized Units

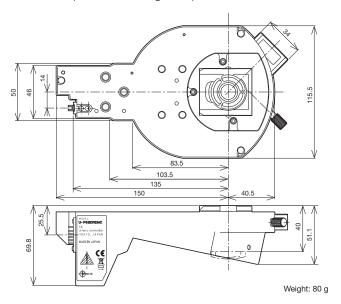
Various motorized units, appropriate for automation of equipment, are available.

U-P5BDREMC

Motorized Centerable Quintuple BD Revolving Nosepiece with Slider Slot for DIC

U-D6BDREMC

Motorized Sextuple BD Revolving Nosepiece with Slider Slot for DIC



U-D5BDREMC

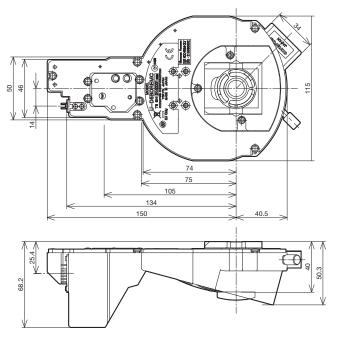
Motorized Quintuple BD Revolving Nosepiece with Slider Slot for DIC

U-D6REMC

Motorized Sextuple Revolving Nosepiece with Slider Slot for DIC

U-P5REMC

Motorized Centerable Quintuple Revolving Nosepiece with Slider Slot for DIC



Control Box for BX2 Series

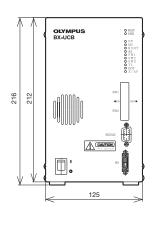
Various motorized units, appropriate for automation of equipment, are available.

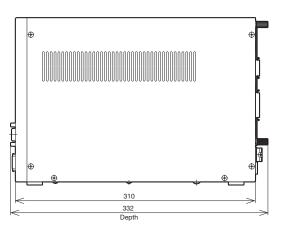
BX-UCB

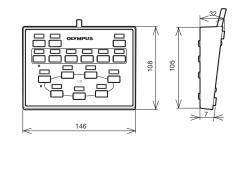
Control Unit

Motorized units including motorized illuminator and auto focus unit can be totally controlled from BX-UCB.

U-HSTR2 Hand Switch







*Extension cord U-RMT (1700 mm) should be used to connect the lamp housing (U-LH100-3) to the BX-UCB.

Weight: 1.0 kg

Cable Length 2000 mm Weight: 370 g

BX-REMCB

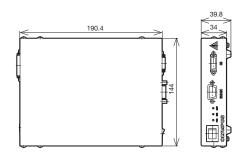
Control Box for Motorized Nosepiece and BF/DF Illuminator

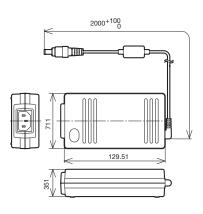
BX-RLAA and U-D5BDREMC/U-D6REMC/U-P5REMC can be controlled from U-HSTR2, or direct from the computer keyboard via an RS232C connector.

*BX-RFAA and U-D5BDREM/U-D6REM combination not applicable.

U-ACAD4515

AC Adapter for BX-REMCB





Weight: kg Weight: kg

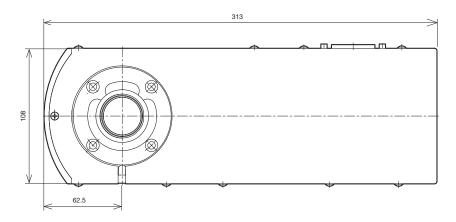
Motorized Units for BX2 Series

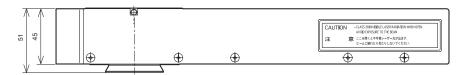
Various motorized units, appropriate for automation of equipment, are available.

U-AFA2M-VIS

Active Auto Focus Unit

Featuring an AF laser light source in wavelength 785 nm. The multiple-spots sensor enables the high-speed and stable focusing of specimens with variable height differences *Class 1 laser product



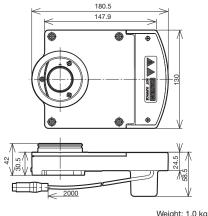


^{*}Consult your Olympus dealer about the motorized focus.

AFA2M-CBL2M Weight: 0.23 kg Length: 2 m AFA2M-CBL3M Weight: 0.36 kg Length: 3 m Weight: 2.6 kg

U-FWR Motorized Reflected Filter Wheel

Accomplish maximum 6 filter position exchange.



Weight: 1.0 kg

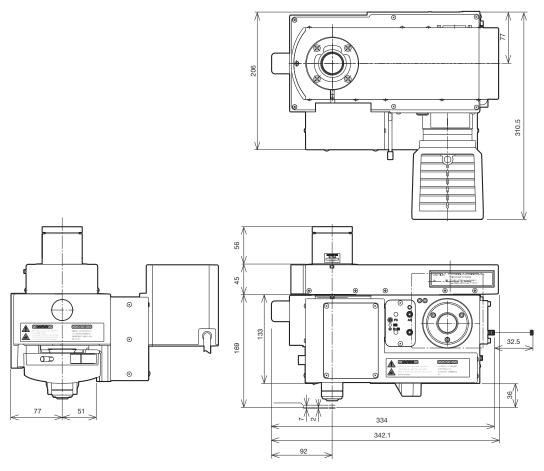
Motorized Modular Microscope

A motorized microscope unit for integration with your equipment. Motorized operations such as revolving nosepiece up/down, objective switching, aperture diaphragm open/close, and brightfield/darkfield switching are accomplished with this component. Several microscopic operations are totally controlled from an external unit by combining this component with an auto focus unit.

BXFMA-F

Motorized Illumination with Power Focus

This is the configuration combined with Active Auto Focus Unit U-AFA2M-VIS, Single Port Tube with Lens U-TLU, a lamp housing, a motorized nosepiece and objectives.



*Consult your Olympus dealer about the mounting dimensions.

Weight: 13 kg (BXFMA-F frame 7.6 kg)

U-FH
Focus Adjustment Knob Unit
Focus Adjustment Knob Interface

Unit: mm

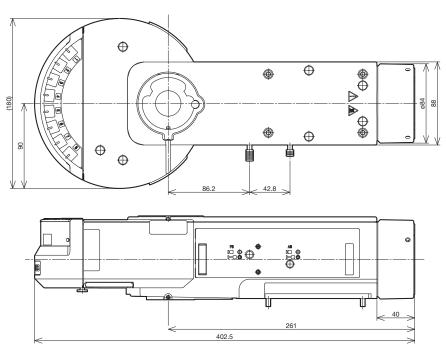
Weight: 1450 g

Weight: 760 g

Motorized Units for BX3 Series

The flexibility of the motorized fluorescence illuminator accommodates multi-color 'stained specimens. The 8-position mirror units permit quick changeover of fluorescence colors.

BX3-RFAAMotorized Fluorescence Illuminator



Weight: 4.2 kg

BX3-UCD8A

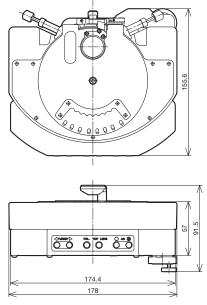
Motorized Universal Condenser

The motorized universal condenser integrates a variety of optical elements to accommodate transmitted light techniques including brightfield, DIC and phase contrast observation.

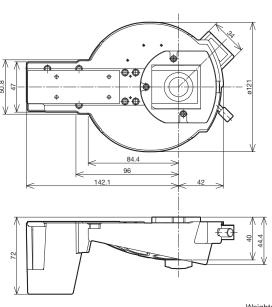
*Optical Elements are required. Please consult your nearest Olympus representative in you region about the Optical Elements Combination.

U-D7REA

Motorized Septuple Revolving Nosepiece with Slider Slot for DIC

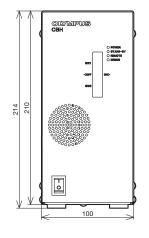


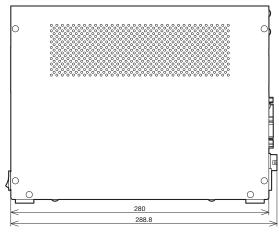


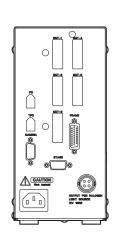


Weight: 1.5 kg Unit: mm

BX3-CBH
Control Box for Fully-motorized Function
Control Box connected to PC via IEEE1394







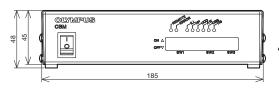
Weight: 4.2 kg

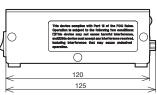
U-CBM

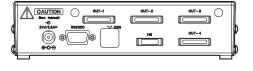
Control Box M for Motorized Function

Control box connected to PC via RS232

*Please consult your nearest Olympus representative in you region about the detailed system chart.







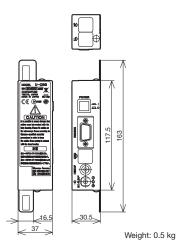
Weight: 0.82 kg

U-CBS

Control Box for Coded Function

Control Box connected to PC via RS232 (attached onto Microscope Frame)

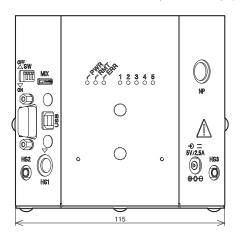
 * Please consult your nearest Olympus representative in you region about the detailed system chart.

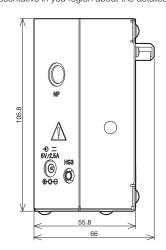


BX3M-CB

Control Box for BXFM

Control Box connected to PC via RS232/USB2.0 (attached onto Microscope Frame) *Please consult your nearest Olympus representative in you region about the detailed system configuration and conbination.







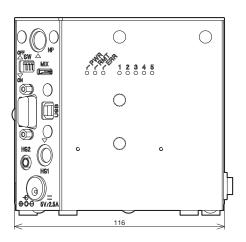
Weight: 0.49 kg

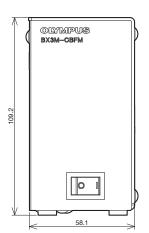
BX3M-CBFM

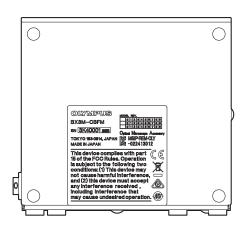
Control Box for BX53M Frame

Control Box connected to PC via RS232/USB2.0

*Please consult your nearest Olympus representative in you region about the detailed system configuration and conbination.







Weight: 0.67 kg

Optical Terminology

1. FN and Practical Field of View

The field number (FN) is referred to as the diaphragm size of eyepiece in mm unit which defines the image area of specimen. The diaphragm diameter actually seen through eyepiece is known as the practical field of view (F.O.V.) which is determined by the formula:

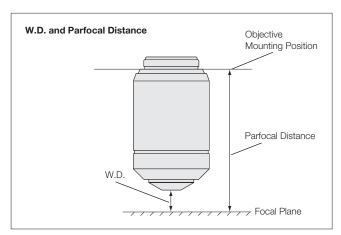
$$F.O.V. = \frac{\text{Eyepiece FN}}{\text{Objective Magnification}} \text{ (mm)}$$

2. W.D.

The distance between the front edge of the objective and the specimen surface (with the surface of the cover glass in case of the cover glass objective) when the specimen is focused.

3. Parfocal Distance

It is the distance between the objective mounting plane and the specimen. In UIS2/UIS objectives, the parfocal distance is designed at 45 mm.



For parfocal distance of the LCPLFLN-LCD series objectives, refer to the appropriate objective page.

4. Relationship Between the Objective's Focal Length and Magnifications

Indicated magnifications of UIS2/UIS objectives are the values when the focal length of the tube lens is 180 mm.

$$M_{(ob)} = \frac{Focal \ Length \ of \ Tube \ Lens}{f}$$

M_(ob): Objective Magnification f: Objective's Focal Length

5. Total Magnification

5.1 Observation Through Eyepiece (binocular observation)

 $M_{\text{(bino)}} = M_{\text{(ob)}} \times M_{\text{(oc)}}$

 $M_{\text{(bino)}}$: Total magnification for binocular observation

 $M_{\text{(ob)}}$: Objective magnification $M_{\text{(oc)}}$: Eyepiece magnification

5.2 Video Monitor Observation

Total Magnification for Video Monitor

 $M_{\text{(video monitor)}} = M_{\text{(ob)}} \times M_{\text{(video camera adapter)}} \times Monitor Magnification*$

 $M_{\text{(video monitor)}}$: Total Magnification on the Video Monitor

M_(ob): Objective Magnification

 $M_{\text{(video camera adapter):}}$ Projected Magnification for Video Camera

Adapter Including Photo Eyepiece

(refer to Figure 1)

*Refer to Figure 3 for "Monitor Magnification"

Practical Field of View for Video Monitor Observation

 $\frac{\text{Practical Field of View for}}{\text{Video Monitor Observation}} = \frac{\text{Image Device Size *}}{M_{\text{(ob)}} \times M_{\text{(video camera adapter)}}}$

M_(ob): Objective Magnification

M_(video camera adapter): Projected Magnification for Video Camera

Adapter Including Photo Eyepiece

(refer to Figure 1 for projected magnifications)

*Refer to Figure 2 for Image Device Size

Figure 1 Video Camera Adapter and Projection Magnifications

3	,
Video Camera Adapter (projection lens)	Projection Magnifications
U-TV1X-1 +	1X
Video Camera Mount Adapters	'^
U-TV1XC	1X
U-TV0.63XC	0.63X
U-TV0.5XC-3	0.5X
U-TV0.35XC-2	0.35X
U-TV0.25XC	0.25X

Figure 2 Imaging Device Size

gaagg							
Camera Format	Diagonal	Horizontal	Vertical				
1/3"	6.0 mm	4.8 mm	3.6 mm				
1/2"	8.0 mm	6.4 mm	4.8 mm				
2/3"	11.0 mm	8.8 mm	6.6 mm				

The above table is for standard image device sizes. Check your device size for precise calculation.

Figure 3 Imaging Device Size and Monitor Magnifications

. Igair o milaging porteo oleo and mornior magnifications						
Comoro Formet	Monitor Size (diagonal)					
Camera Format	10"	15"	17"	19"	21"	
1/3"	42.3X	63.5X	72.0X	80.4X	88.9X	
1/2"	31.8X	47.6X	54.0X	60.3X	66.7X	
2/3"	23.1X	34.6X	39.3X	43.9X	48.5X	

Example

What is total magnifications for video monitor when objective is 50X, video camera adapter U-TV0.5XC, 2/3" video camera and 21" monitor are used ?

Optical Terminology

•Total magnification on the video monitor:

 $M_{\text{(ob)}}=50X$, $M_{\text{(video camera adapter)}}$ is 0.5X from Figure 1 and monitor magnification is $48.5\times$ from Figure 3.

 $M_{\text{(monitor observation)}} = M_{\text{(ob)}} \times M_{\text{(video camera adapter)}} \times \text{monitor magnification} = 50 \times 0.5 \times 48.5 = 1213 \times$

• Practical filed of view for video observation (horizontal side): M(ob)=50X, M_(video camera adapter) is 0.5X from Figure 1 and horizontal side of 2/3" imaging device is 8.8mm from Figure 2

$$\frac{\text{Practical Field of View}}{\text{for Video Observation}} = \frac{\text{Image Device Size}}{M_{\text{(ob)}} \times M_{\text{(video camera adapter)}}}$$

$$=\frac{8.8 \text{ (mm)}}{50 \times 0.5} = 52 \text{ }\mu\text{m}$$

6. NA

The numerical aperture is a key factor to the performance of objective (resolving power, focal depth and brightness). The NA is determined by the following formula:

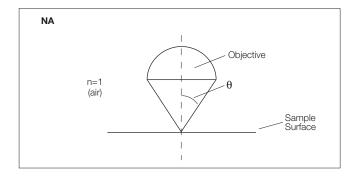
$$NA = n \times sin\theta$$

n=Refraction Rate of the Medium between Specimen and Objectives. (Air: n=1, oil: n=1.515)

θ: Angle Which is Made by the Optical Axis and Refraction of the Light Farthest from the Center of the Lens.

The visual field brightness (B) of the microscope is determined by the following formula in relation to the objective magnification (M). The larger the NA and the lower the objective magnification, brightness will increase in the factor of the second power.

$$B\!\approx\!\frac{NA^2}{M^2}$$



7. Resolving Power

The resolving power of an objective is measured by its ability to differentiate two lines or points in an object. The greater the resolving power, the smaller the minimum distance between two lines or points that can still be distinguished. The larger the NA, the higher the resolving power.

Resolving Power Formula

The following formula is generally used for determing resolution.

$$\epsilon$$
 =0.61× $\frac{\lambda}{NA}$ (Reyleigh formula)

 $\lambda :$ Wavelength or Radiation in Use ($\lambda {=} 0.55~\mu m$ is used for visible light.)

NA: Objective NA

Example

MPLFLN100X (NA=0.90), λ =0.55 μ m

$$\epsilon = 0.61 \times \frac{\lambda}{NA} = \frac{0.3355}{NA} = \frac{0.3355}{0.90} = 0.37 \ \mu m$$

8. Focal Depth of Microscope

The focal depth refers to the depth of the specimen layer which is in sharp focus at the same time, even if the distance between the objective and the specimen plane is changed when observing and shooting the specimen plane by microscope. As human eyes are individually different in the ability of their focus adjustment, each person's perception of the focal depth varies.

At present, the Berek formula is generally used, because it gives a focal depth value that often coincides with that obtained through experiments.

Focal Depth formula

Visual Observation (Berek formula)

$$\pm \text{ D.O.F.} = \frac{\omega \times 250,000}{\text{NA} \times \text{M}} + \frac{\lambda}{2 \text{ (NA)}^2} \text{ (µm)}$$

D.O.F.: Depth Of Focus

ω: Resolving Power of Eyes 0.0014 (when optical angle is 0.5 degrees)

M: Total Magnification

(objective magnification x eyepiece magnification)

⇒ ± D.O.F. =
$$\frac{350}{\text{NA} \times \text{M}} + \frac{0.275}{\text{NA}^2}$$
 (λ =0.55 µm)

This indicates that the focal depth becomes smaller as the numerical aperture becomes larger.

Example

With MPLFLN100X (NA=0.90), WHN10X:

$$\pm$$
 D.O.F. = $\frac{350}{0.90 \times 1,000} + \frac{0.275}{0.81} = 0.39 + 0.34 = 0.73 \ \mu m$

Video Camera

In the case of a video camera, the focal depth will vary according to number of pixels of CCD, optical magnification, and numerical aperture. The above-mentioned formula is used as a rough guide only.

9. Aberrations

A difference between an ideal image and an actual image that passes through an optical system is called an "aberration."

9.1 Requirements for Ideal Image Formation

The following three requirements must be satisfied to form an image with no aberration, or an ideal image.

- (i) All the light rays coming from a single point and passing through an image formation optical system converge on a single point.
- (ii) Image points, which correspond to object points on the same plane perpendicular to the optical axis, are present on the same plane.
- (iii) The planar shape of an object and the planar shape of an image that are on the same plane perpendicular to the optical axis have a similarity relation.

Figure 9-1 Requirements for Ideal Image Formation

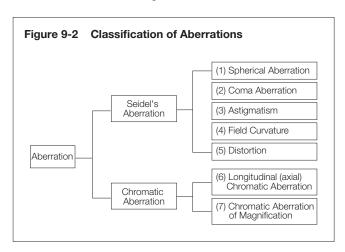
Object Image Plane

In an actual optical system, however, it is very difficult to strictly meet the requirements for ideal image formation and this causes "aberrations" that interfere with image forming performance.

9.2 Classification of Aberrations

Aberrations that interfere with image forming performance are classified as shown below in Figure 9-2.

Seidel's Aberration = "Expansion of a Point Image" + "Curvature of Image Plane" + "Deformation"



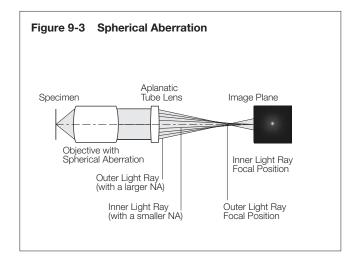
Types (1) to (3) correspond to "expansion of a point image" that goes against requirement (i) for ideal image formation in Figure 9-1. Type (4) corresponds to "curvature of image plane" that goes against requirement (ii) in Figure 9-1.

Type (5) corresponds to "deformation" that goes against requirement (iii) in Figure 9-1.

Types (6) and (7) correspond to "color blur" of images caused by characteristics of glass materials used for the optical system. "Expansion of a point image" can also be expressed by "wavefront aberration" that regards the light as "waves" and takes account of the phase to include the influence of diffraction

(1) Spherical Aberration

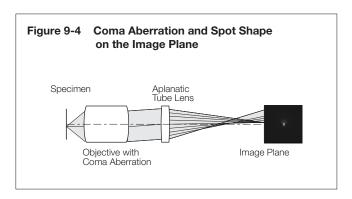
When light rays coming out of an axial object point enter a lens, the light rays with a larger numerical aperture (NA) are subjected to stronger refraction power and cross the optical axis in positions with larger differences from the ideal image formation position. The aberration caused this way by different image forming positions due to differences in NA of axial light rays is called "spherical aberration." ("Spherical aberration" is proportional to the cube of NA)



It is said that objectives with larger NA have better resolution but worsen spherical aberration. Our advanced design and manufacturing techniques have realized good optical performance even with large numerical aperture.

(2) Coma Aberration

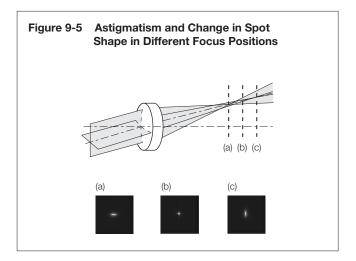
Even though spherical aberration is compensated to be very small, there are cases where light rays coming out of an off-axis object point are not condensed to a single point on the image plane but generate asymmetric blur just like a comet leaving traces. This is called coma aberration.



Optical Terminology

(3) Astigmatism

Even though a lens is compensated for spherical aberration and coma aberration, there are cases where an image of an off-axis object point is not focused to a single point but separated to a concentric line image and a radial line image. This is called "astigmatism." When astigmatism is present, a point image blurs vertically and horizontally, before and after the focus position.



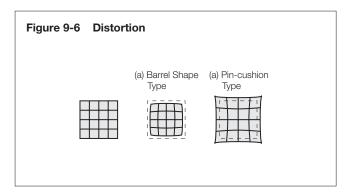
(4) Field Curvature

An image plane of an object on a plane perpendicular to an optical axis does not always become a plane perpendicular to the optical axis, but it generally becomes a curved plane. This symptom is called "field curvature."

When field curvature is present, the image is more displaced as it becomes closer to the periphery of the visual field. Therefore, when the center of an image is brought into focus, blur occurs in the peripheral areas of the image. To bring the entire image, including the periphery, into clear focus, it is necessary to adequately compensate for this type of aberration.

(5) Distortion

When there is no similar relation between a planar shape on an object and a shape on the image plane, this is called "distortion." When distortion is present, a square image appears in a shape of a barrel or pin-cushion as shown in Figure 9-6.



The microscope optical system contains some distortion. When distortion is present, it can bring erroneous results of shape measurements. When a microscope is used for precision measurements, pay close attention to this aberration, for example, by providing it with an aberration compensation function.

(6) Chromatic Aberration

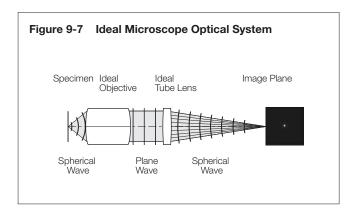
Glasses used for optical systems have different refractive indexes depending on the wavelength. This causes differences in focal length between wavelengths and generates displacement of image forming position. This phenomenon is called "chromatic aberration," which is sometimes subdivided into axial displacement on the optical axis, called "axial chromatic aberration" (or lateral chromatic aberration) and displacement on the image plane, called "chromatic aberration of magnitude."

Many special glass materials are used, e.g., for apochromats, to eliminate chromatic aberration in a wide range from violet light (g-rays with wavelength of 435 nm) to red light (c-rays with wavelength of 656 nm).

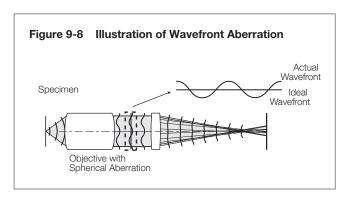
9.3 Wavefront Aberration

Since a long time ago, aberrations have been used in "geometric optics," which considers light as "light rays." Microscope optical systems are often used for observation of very small specimens at a wavelength level, and sometimes adopt "wave optics," which regards light as "waves" and handles the phase information, taking account of the influence of diffraction.

In such a case, "wavefront aberration" is used for evaluation. As shown below, when requirements for ideal imaging are satisfied in a microscope optical system, the spherical wavefront (spherical waves) coming from a single point on an object (specimen) is converted to plane waves through an ideal objective. The plane waves are converted to spherical waves through an ideal tube lens, and condensed to a single point. The wavefront of these waves is called the "ideal wavefront."



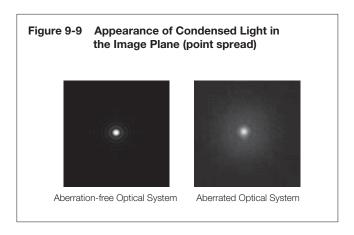
Based on the figure indicated for (1) spherical aberration, the behavior of the wavefront in an optical system that has an aberration is described below.



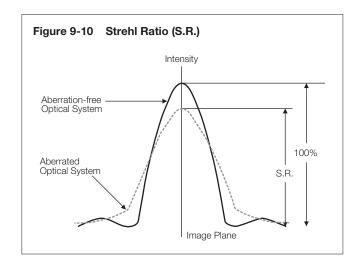
A difference (a degree of disagreement) between the ideal wavefront and the actual wavefront shown above is called "wavefront aberration."

9.4 Strehl Ratio

When a point light source is observed with an aberration-free optical system and an aberrated optical system, the former concentrates the focal point to a point at the image formation position. In contrast, the latter fails to produce a focal point, instead causing a spread in the intensity distribution of the point image (this is known as "point spread"). The specific appearance of such a point image (i.e. point spread) is shown in Figure 9-9.



With the proportion of light concentrated in the image plane (intensity of light concentrated in the Airy disk) by an aberration-free optical system serving as 100%, the proportion of light concentrated by an aberrated optical system is known as the Strehl ratio. When graphed, the Strehl ratio reveals peaks in intensity as shown in Figure 9-10. The higher the S.R., the closer an optical system is to being aberration-free.



A Strehl ratio of 80% is typically called the diffraction limit, and lenses with a lower ratio lack the performance required to serve as an objective. A ratio of over 95% means that the lens' performance in general observations is comparable to that of an aplanatic lens (which is corrected for spherical aberrations and coma).

Note: A laser interferometer is used for actual assessment of optical performance, so assessment is done at a single wavelength. Unless otherwise noted, Strehl ratio measurements are at the e-line (544 nm).

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